

# Silicon Photonics, Hybrid Integration, and Frequency Combs: Technologies for High-Bandwidth Communications

Christian Koos



Alfried Krupp  
von Bohlen und Halbach - Stiftung

**KSOP**

Wave phenomena  
analysis and numerics

**PIXAPP**  
Photonic Packaging  
Pilot Line



erc  
TeraSHAPE

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*Vanguard Photonics GmbH, Karlsruhe, Germany*



## Introduction

- Scalability challenges in optical communications
- Silicon photonics and the need for hybrid integration

## Silicon-based building blocks for high-bandwidth transceivers

- Waveguides and passive devices
- Photodetectors
- Light sources
- Modulators

## Packaging and system assembly

- Coupling interfaces to silicon photonic waveguides
- In-situ waveguide fabrication by 3D laser lithography

## Silicon photonic transceivers

- Commercial products and experimental demonstrations
- Towards massively parallel WDM transceivers

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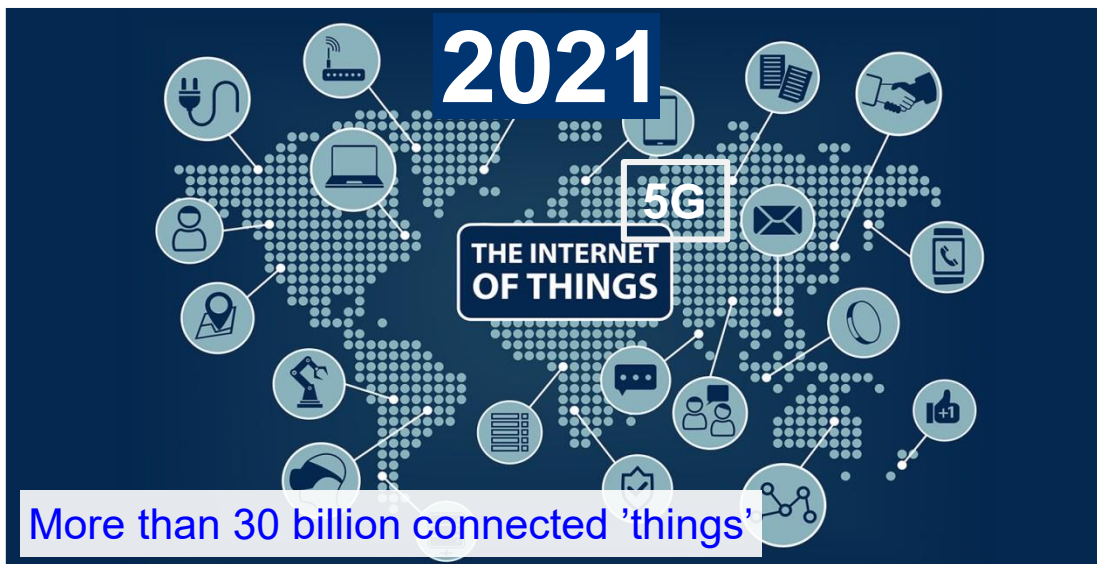
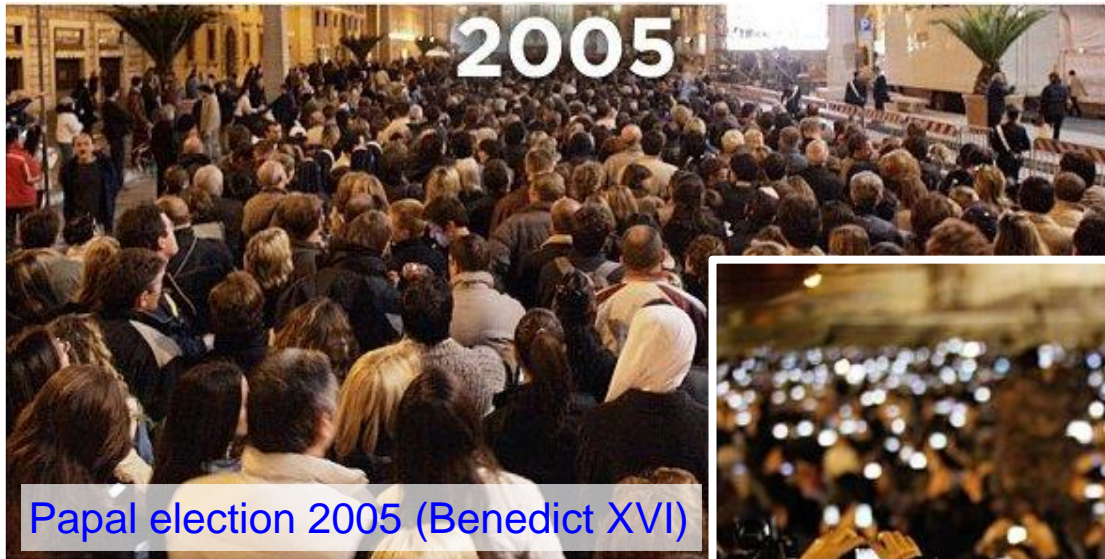
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# The need for high-speed communications...



Picture sources: NBC, IT Pro



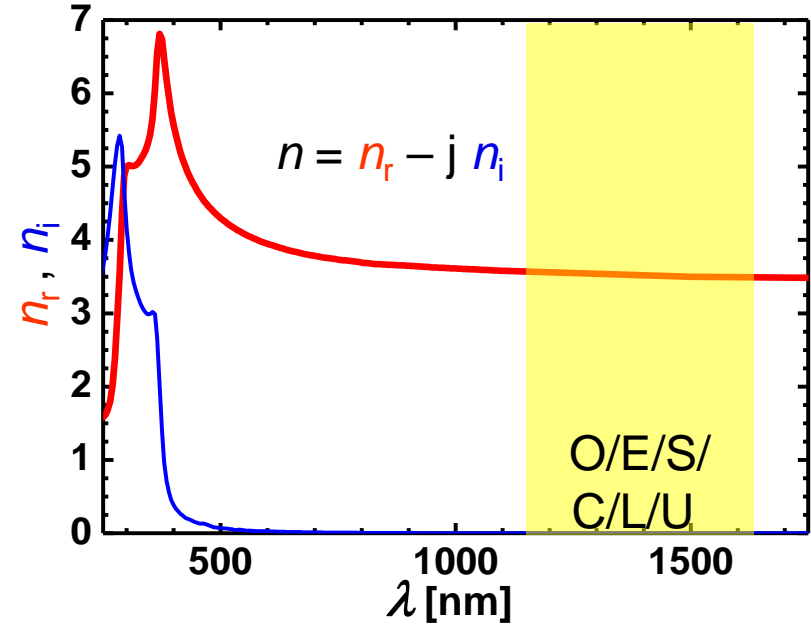
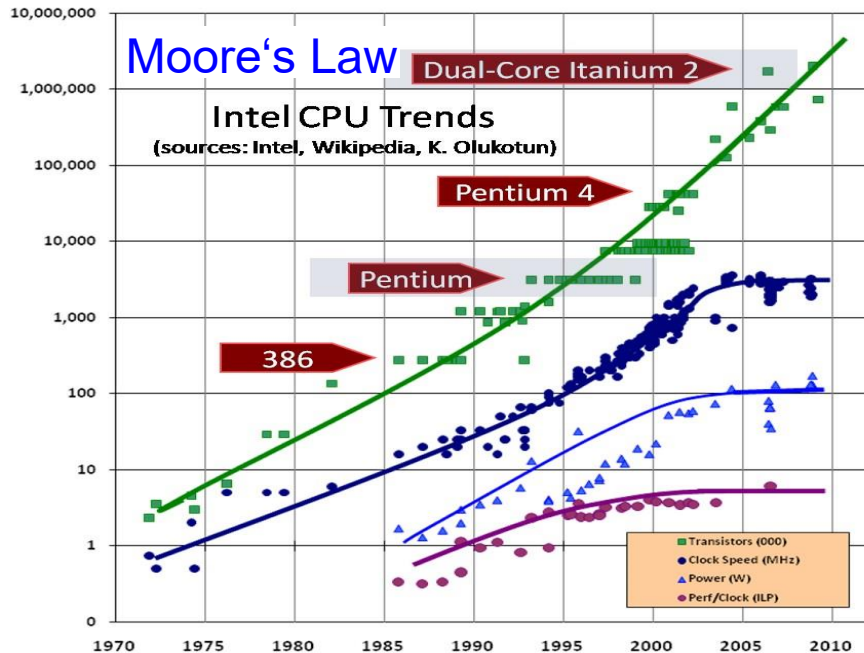
Towards ubiquitous connectivity in data-center, campus-area, and edge networks

- VCSEL for “short connections”
- Silicon photonics for “longer reach” (> 300 m)
- Massively parallel wavelength division multiplexing (WDM)

# Why silicon?

## Silicon:

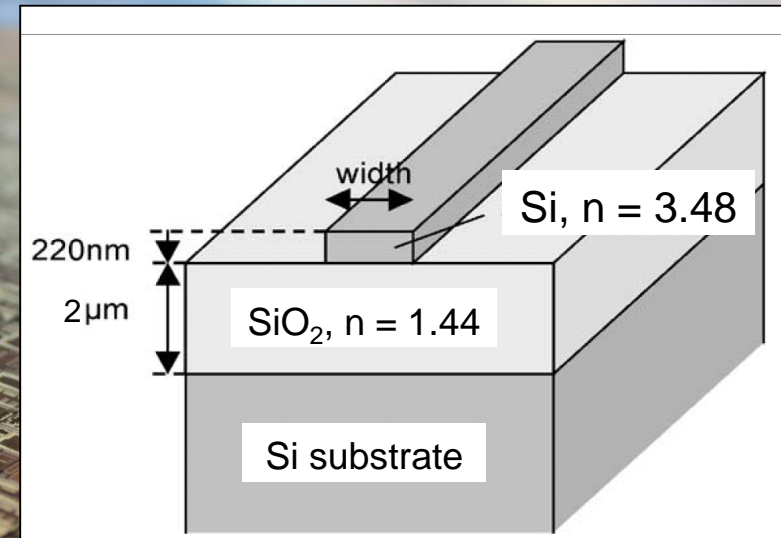
- Transparent at IR telecom wavelengths
- High refractive index
  - ⇒ Nanophotonic devices
  - Dense integration
  - Small active volumes
  - Ultra-fast low-power switching



- Availability of sophisticated CMOS fabrication processes
  - ⇒ Low-cost high-yield mass-production
  - Joint integration of photonics and electronics

# Silicon photonics: Strengths

- High-index-contrast SOI waveguides  
 ⇒ High integration density
- Mature CMOS technology  
 ⇒ Large-scale photonic-electronic integration with high yield
- Ecosystem of foundries  
 ⇒ Fabless fabrication: Share investment and development costs by multi-project-wafer (MPW) runs and process design kits (PDK)



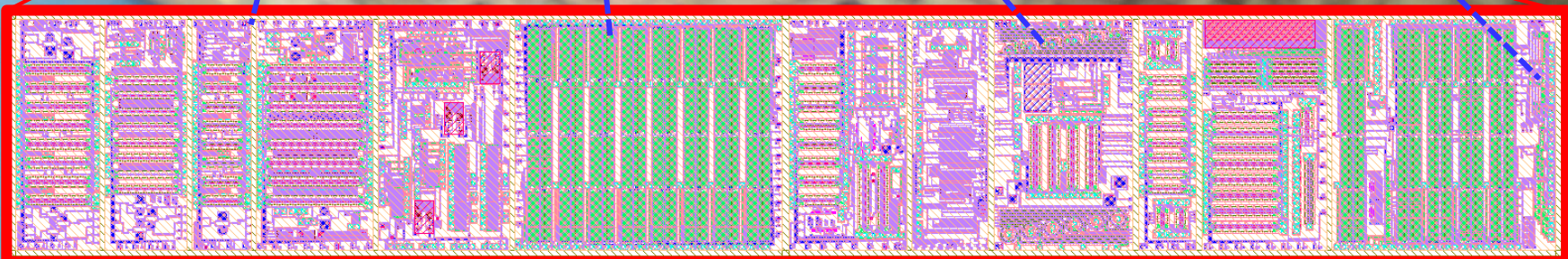
(4 x 25) mm<sup>2</sup>

Photodetectors

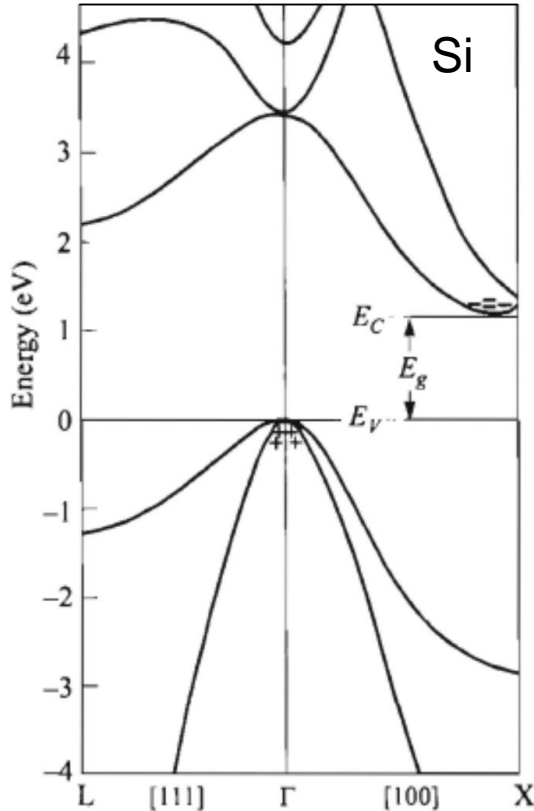
Electro-optic modulators

Biosensors

Optical coherence tomography (OCT) engines

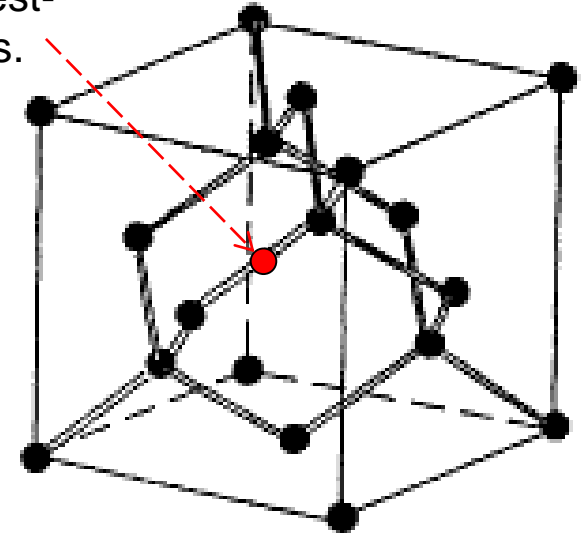


Indirect bandgap inhibits light emission



No Pockels effect due to inversion symmetry of the diamond crystal lattice

**Inversion point:**  
Mid-point of nearest-neighbour bonds.



$$T_{q'q} = -\delta_{q'q}$$

$$\Rightarrow \chi_{q_0:q_1\dots q_n}^{(n)} = (-1)^{n+1} \chi_{q_0:q_1\dots q_n}^{(n)}$$

$$= 0 \quad \text{for even } n.$$

⇒ External lasers of hybrid integration of direct-bandgap III-V materials on silicon

⇒ Hybrid integration of electro-optic materials on silicon chips or alternative techniques to modulate the refractive index in silicon

Quelle: Sze, Semiconductor Devices



# Bierdeckel-Rechnung (“back-of-the envelope” calculation)

## SiP TRx market in 2023:

18 million 100 Gbit/s TRx, 5 mm<sup>2</sup> each

⇒ 90 million mm<sup>2</sup>

⇒ 3000 pieces of 8“ wafers (30 000 mm<sup>2</sup>)

## CMOS fab capacity 2018\*:

TSMC: 12 million 12“ wafers in 11 fabs in 2018

⇒ 120 wafer/h/fab in 2018 (12“!!!)

⇒ Annual SiP Ethernet TRx supply forecasted for 2023 can be produced within 25 h using 2018 equipment of a single fab.

## Overall market volumes:

SiP prediction for 2023:  
(w/o laser integration) 650 million \$

Electronic CMOS IC in 2023: > 400 billion \$

⇒ “High-volume” SiP transceivers will not by no means be a “volume business” for CMOS fabs!

\*[https://www.tsmc.com/english/dedicatedFoundry/manufacturing/fab\\_capacity.htm](https://www.tsmc.com/english/dedicatedFoundry/manufacturing/fab_capacity.htm)

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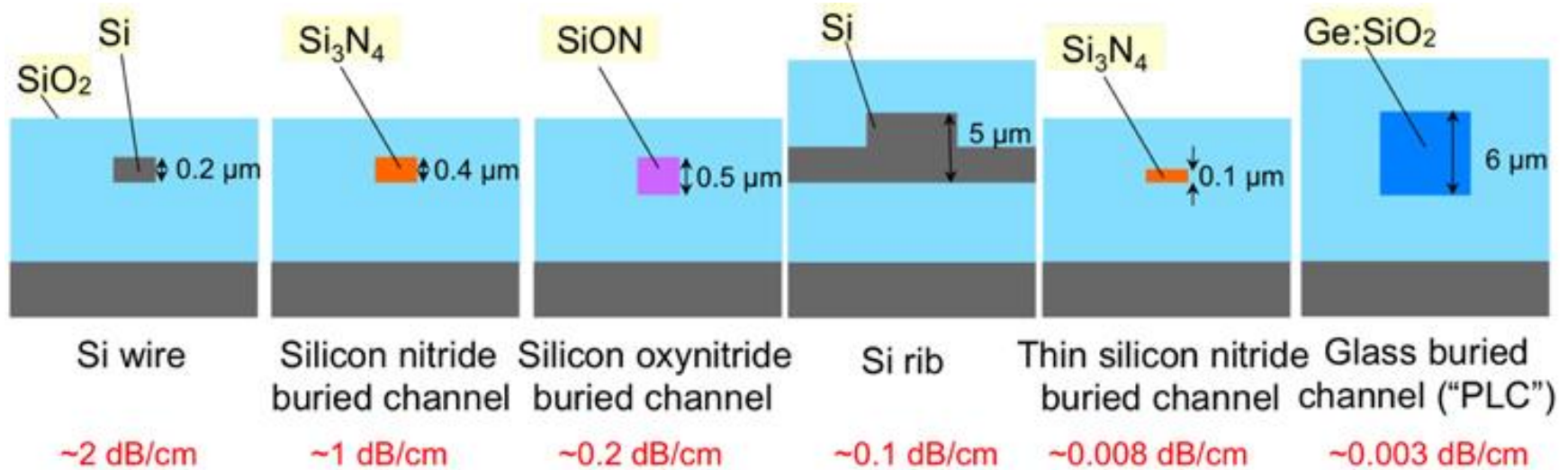
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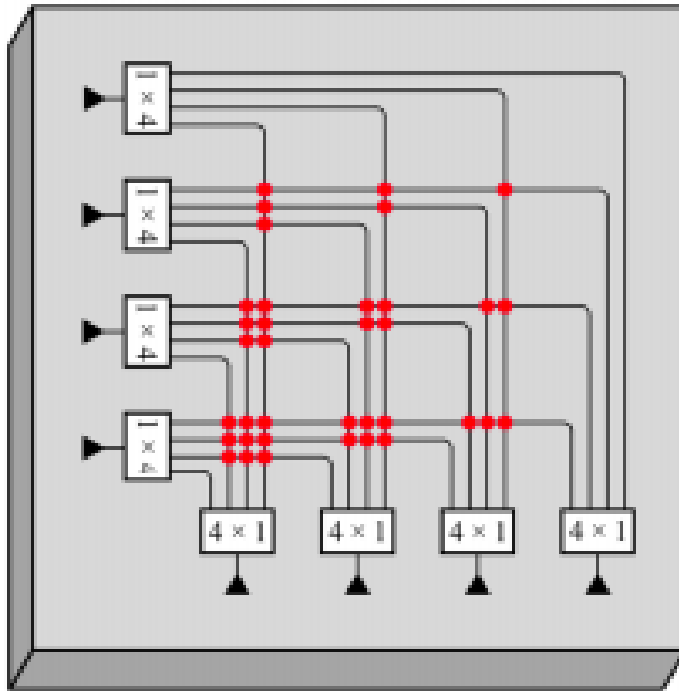
Si:  $n = 3.48$   
 SiO<sub>2</sub>:  $n = 1.45$   
 Si<sub>3</sub>N<sub>4</sub>:  $n = 2.0$



Standard designs of passive devices (bends, directional couplers, multi-mode interference couplers) are often offered in the process design kit (PDK).

Doerr et al., *Frontiers in Physics*, **3**, 37 (2015)

Example: Non-planar switch-and-select circuit



Number of waveguide crossings in planar circuit technology:

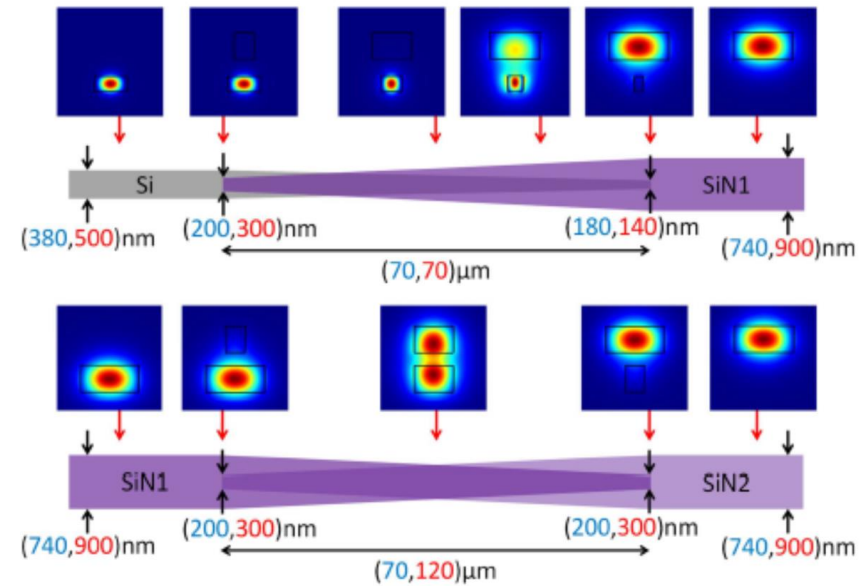
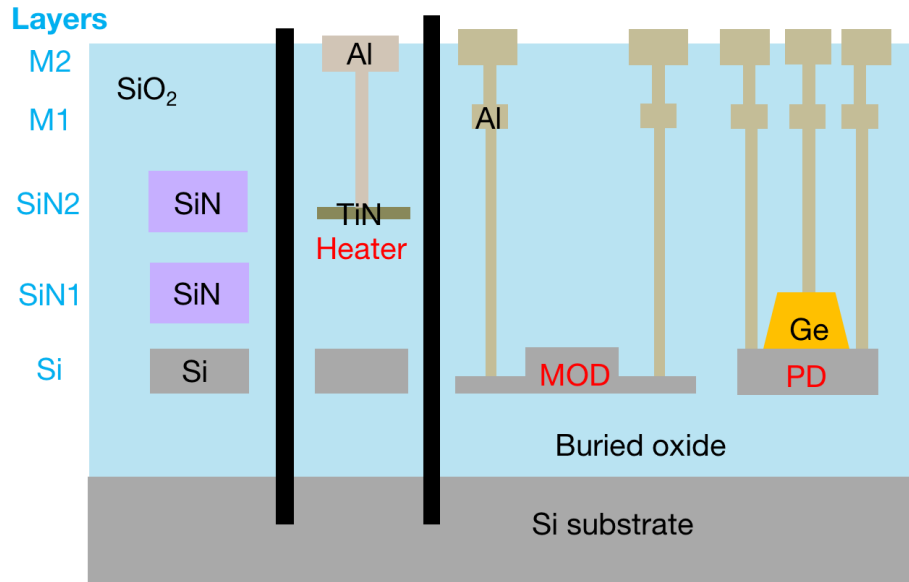
$$\eta_{n,n}^{(\text{basic})} = \left( \frac{n(n-1)}{2} \right)^2$$

⇒ Avoid waveguide crossings by 3D overpasses

Nesic *et al.*, arXiv:1901.08309 (2019)

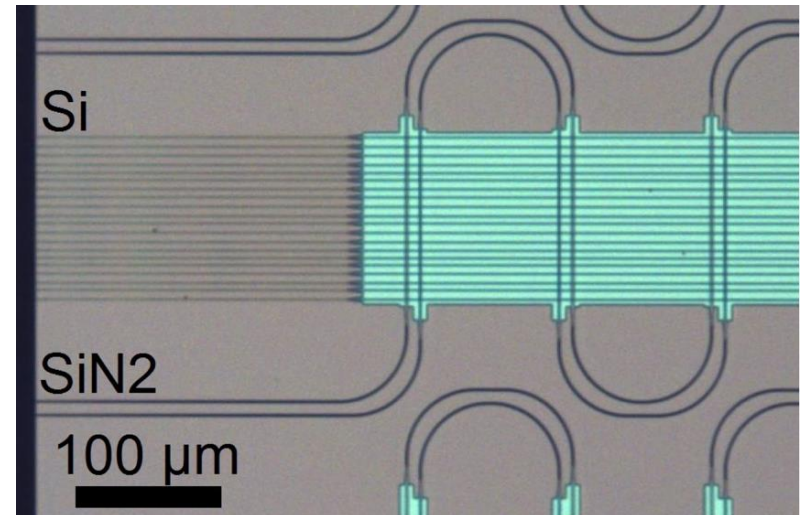
Sacher *et al.*, Proc. IEEE., 2232 – 2245 (2018)  
Chiles *et al.*, APL Photonics 2(11), (2017).

# Multi-layer silicon photonic circuits



- Up to 2 SiN waveguide layers integrated on Si using LPCVD (“FEOL”) or PECVD (“BEOL”)
- Adiabatic tapers for inter-layer power transfer
- Loss: < 3 mdB per crossing
- Crosstalk: < -60 dB

Sacher *et al.*, Proc. IEEE **106**, 2232 – 2245 (2018)



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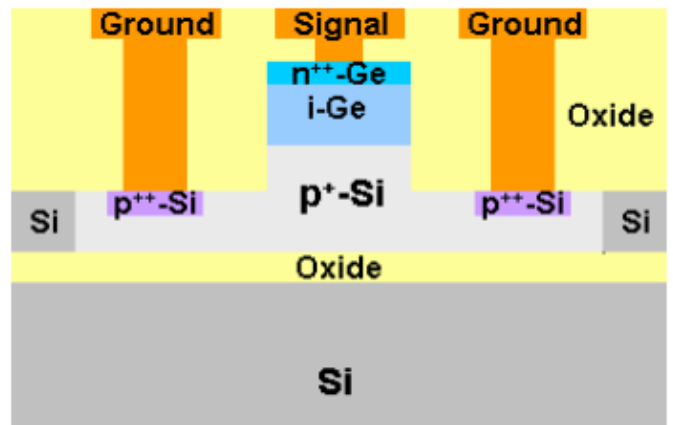
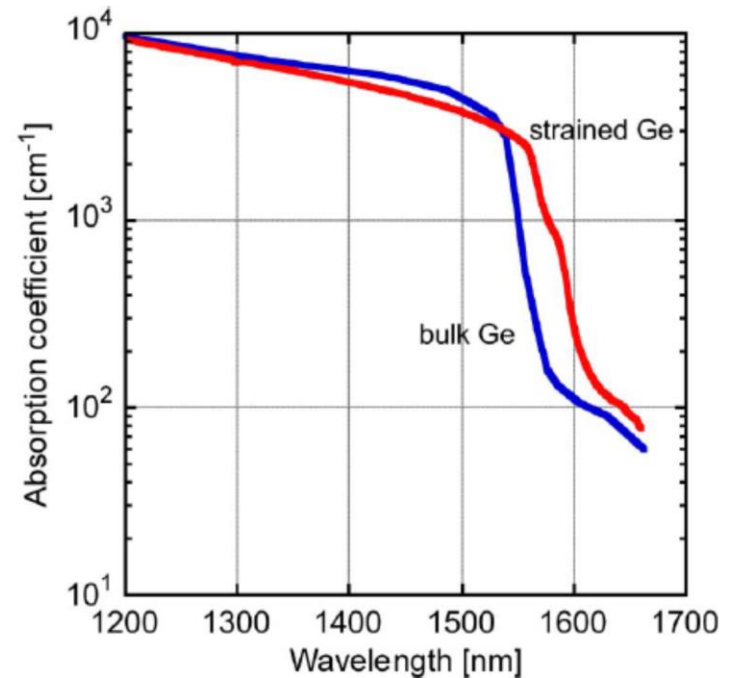
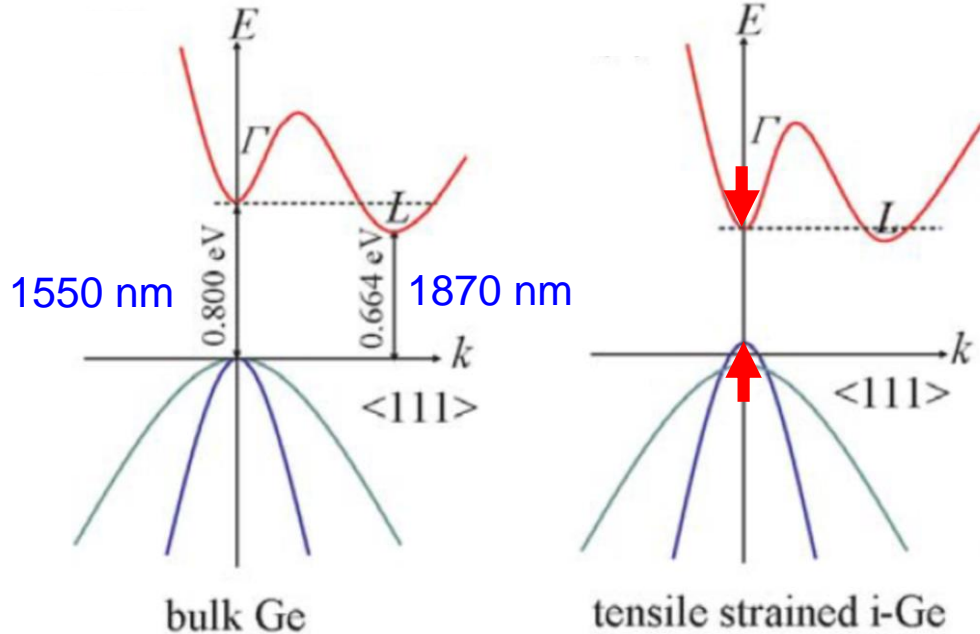
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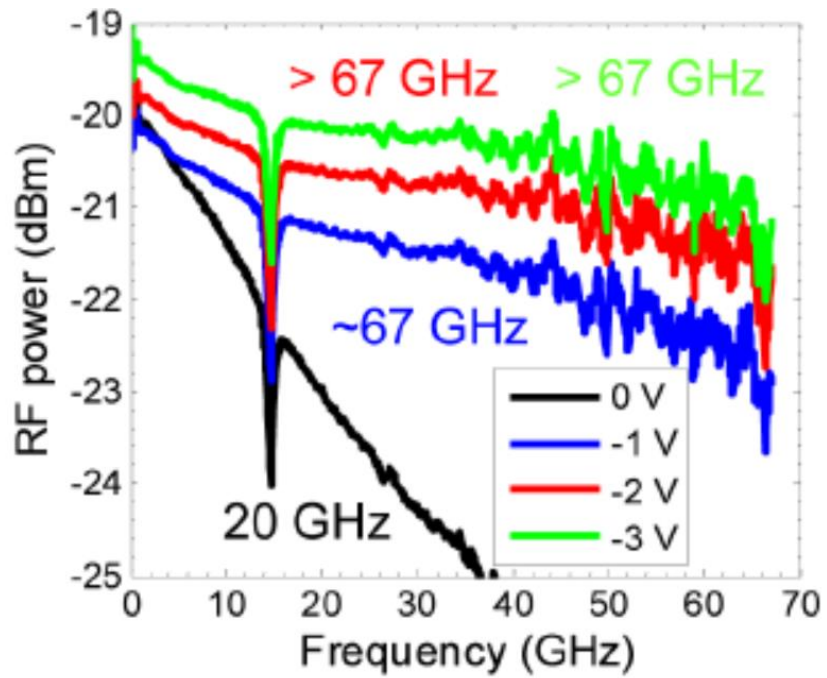
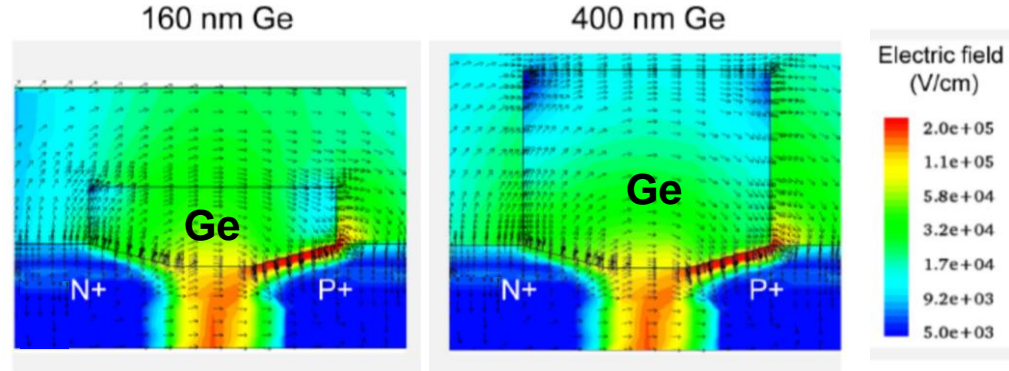
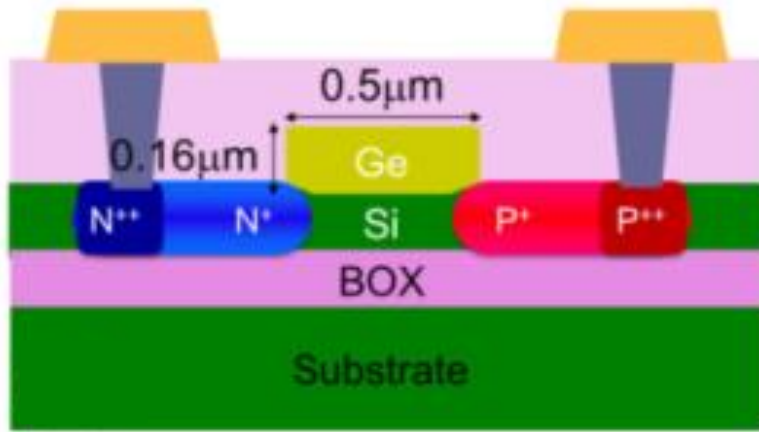
## Summary

# Silicon-germanium photodetectors



- Fabricated by SiGe heteroepitaxy
- Absorption at 1.55  $\mu\text{m}$  enhanced by strain-induced reduction of the band spacing at the  $\Gamma$ -valley
- **Responsivity:** 1.16 A/W @  $\lambda = 1,55 \mu\text{m}$ ,  $L = 20 \mu\text{m}$
- **Bandwidth:**  $\sim 30 \text{ GHz}$  @  $-2 \text{ V}$  bias (limited by both transit time and RC time constant)

Sun *et al.*, ECS Transactions **16** (10) 881-889 (2008)  
 Colace *et al.*, IEEE Photonics Journal **1**, 69–79 (2009)  
 Yin *et al.*, Opt. Express **15**, 13965 - 13971 (2007)



No metal contact on Ge

- No light absorption from metal
- No doping of Ge required

Thin Ge layer (160 nm)

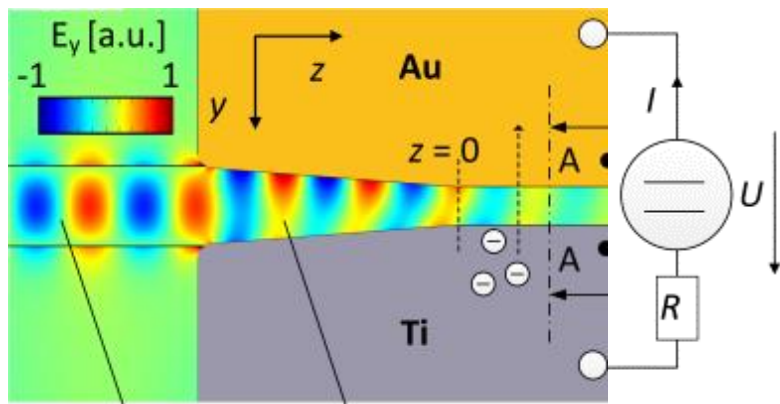
- High electric field inside Ge:  
 $E > 10^4$  V/cm @ 1 V bias
- Carrier drift at saturation velocity for “CMOS-compatible” bias voltage.
- $f_{3dB} = 67$  GHz, limited by transit time  
Potential to increase further

Responsivity: 0.74 A/W @  $\lambda = 1.55 \mu\text{m}$

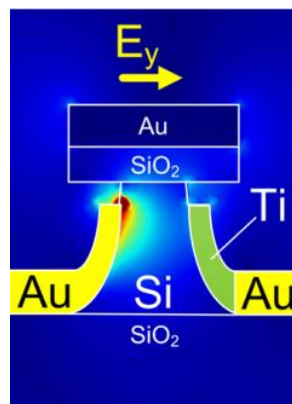
Chen *et al.*, Opt. Express **24**, 4622 - 4631 (2016)



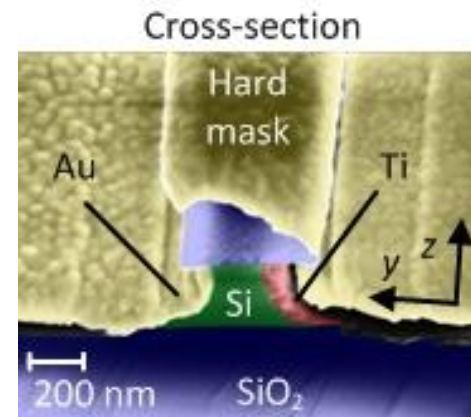
# Plasmonic internal photoemission detectors (PIPED)



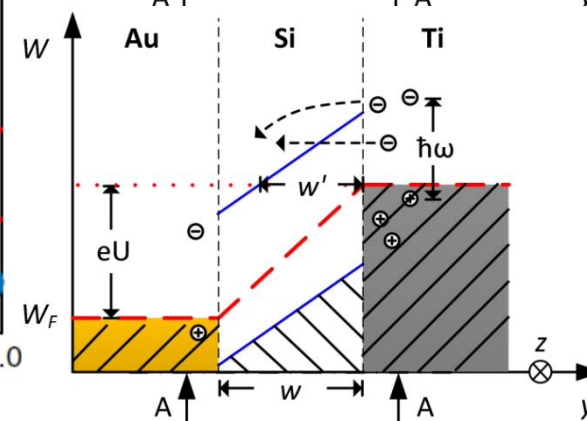
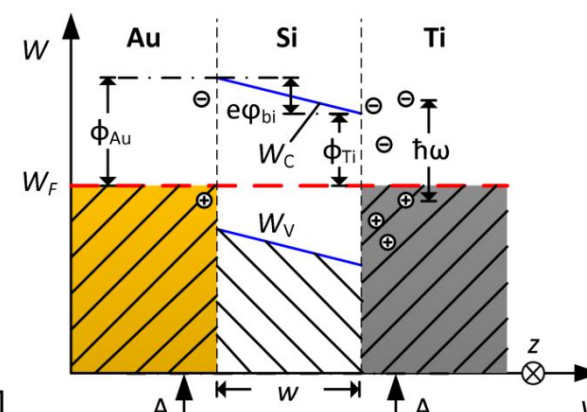
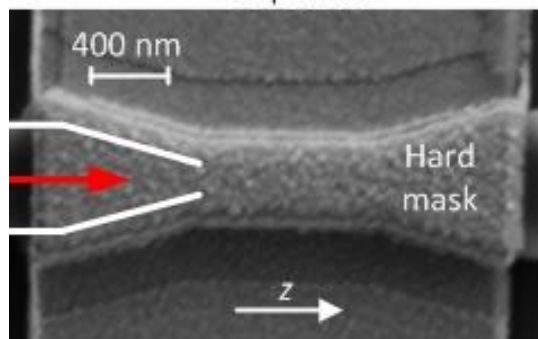
Si photonic waveguide      Photonic-to-plasmonic mode converter



Top view

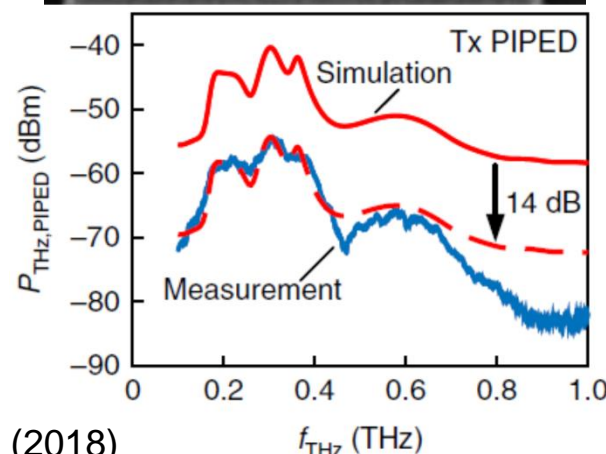


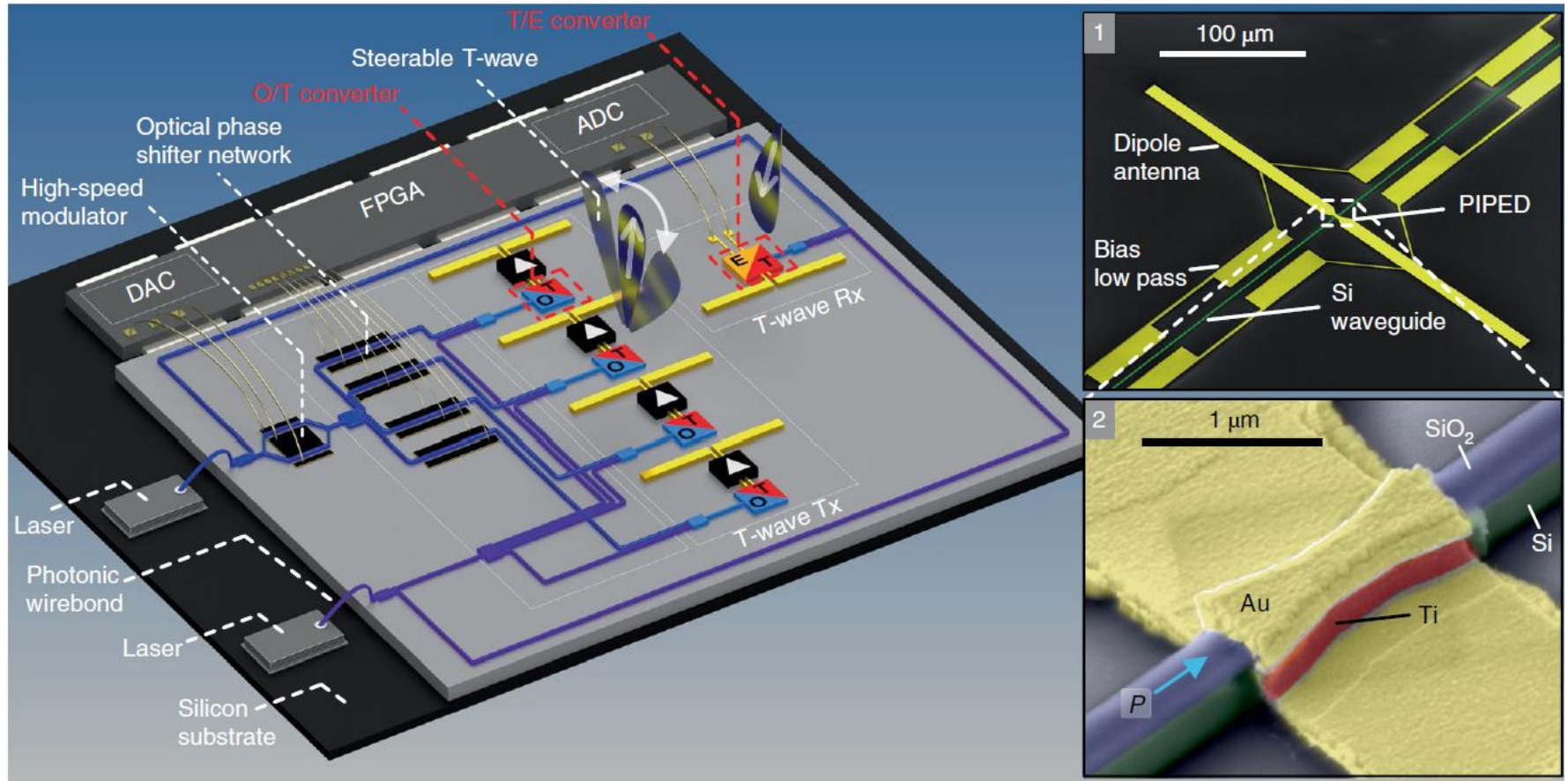
Cross-section



- Internal photoemission from Ti into adjacent ultra-thin Si drift region (~ 100 nm)
- Ultra-small lateral dimensions minimize capacitance (< 1 fF)

⇒ Ultra-fast response, enabling optoelectronic generation of THz signals





Harter *et al.*, Nature Photonics **12**, 625–633 (2018)

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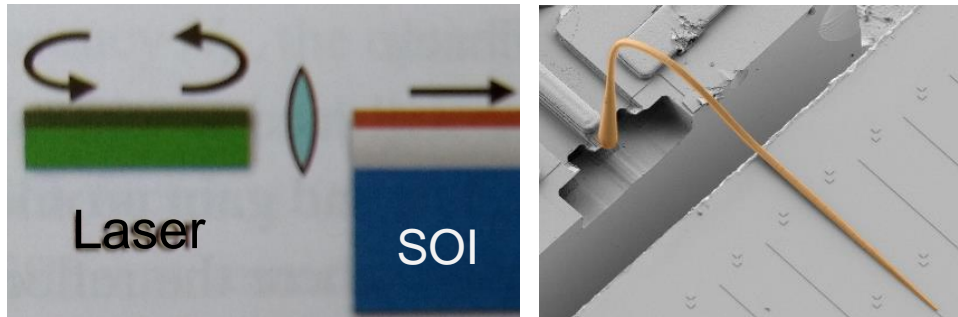
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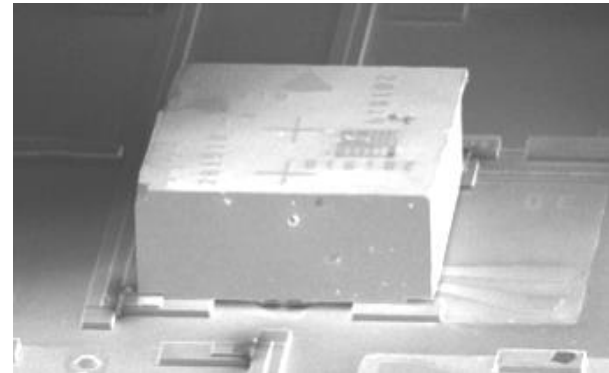
# Light sources for silicon photonics

**Co-packaging or hybrid multi-chip integration**  
e.g., by high-precision alignment or by 3D-printed waveguides (“photonic wire bonds”)



Billah *et al.*, *Optica* **5**, 876-883 (2018)

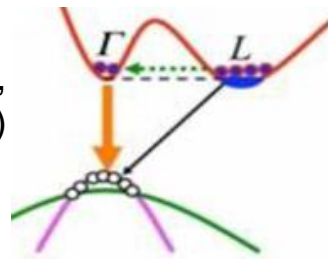
**Mounting of pre-made lasers to SiP chip**  
e.g., by active alignment



Mitze *et al.*, *Int. Conf. on Group IV Phot.* 2005

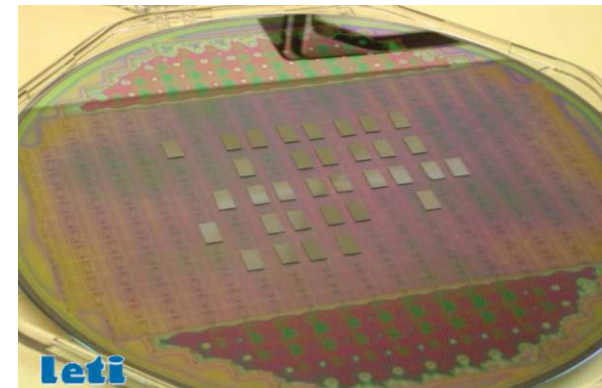
## Monolithic integration

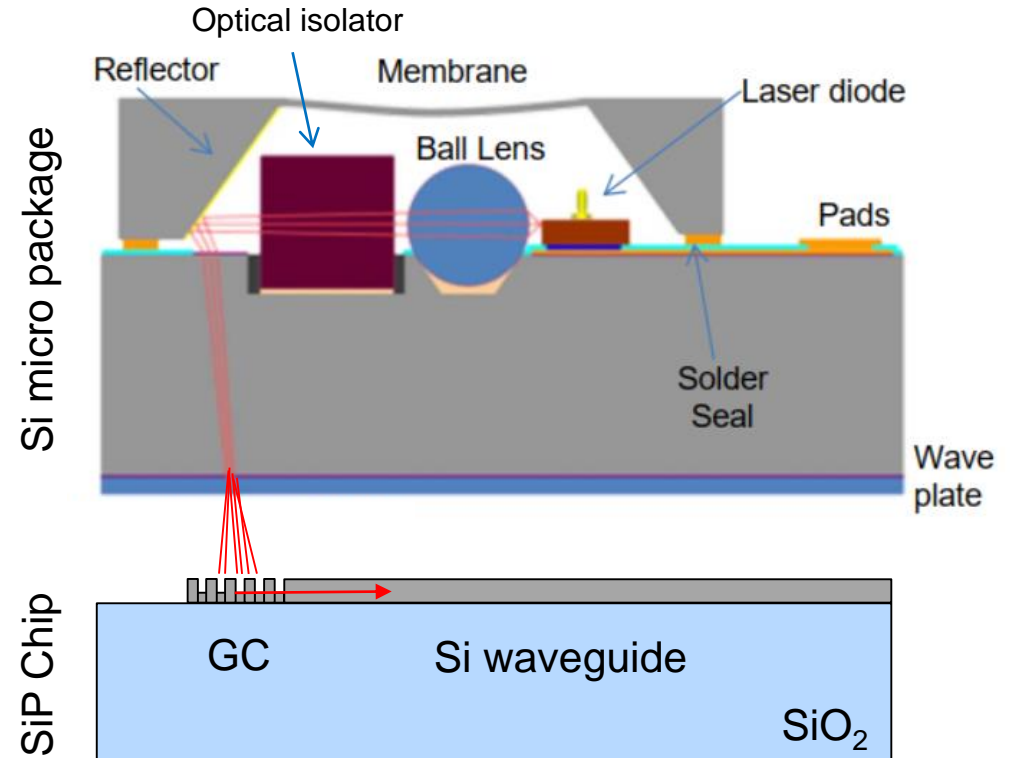
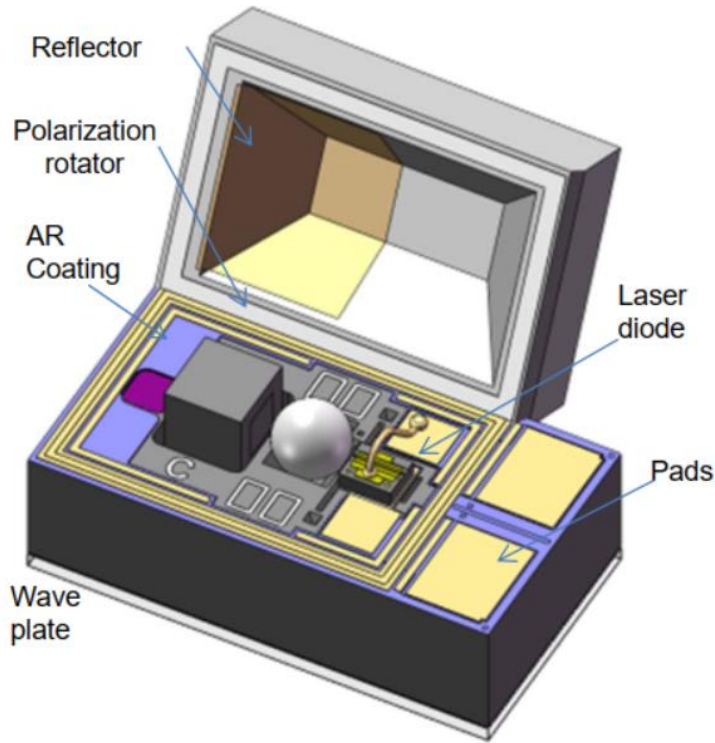
- Er-doped Si nanocrystals  
Zhizhong *et al.*, *Proc. IEEE* **97**, 1250 (2009).
- Stimulated Raman scattering  
Rong *et al.*, *Nature Phot.* **1** 232-237 (2007)
- Light emission in strained Ge  
Liu *et al.*, *Opt. Lett.* **35**, 679–681 (2010)
- Epitaxial growth of III-V-materials on silicon



## Heterogenous integration of III-V materials

Wafer-bonding of blank III-V-dies + collective processing



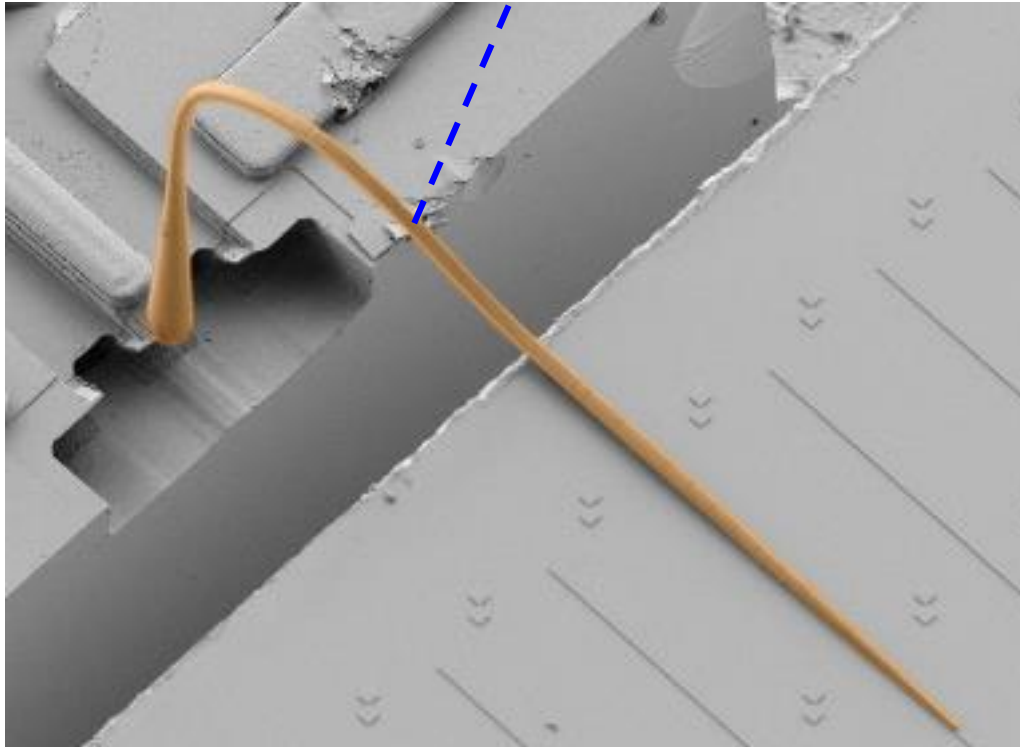


- Commercially used by Luxtera
- Silicon micro-machined laser diode housing for coupling, comprising lens and isolator
- Flexible: Use individually optimized laser diode from any supplier
- Allows for testing of devices prior to assembly
- Requires active alignment

Luxtera, *ECOC* (2014)

Snyder et al. al *J. Light. Technol.* **31** (2013)

3D-printed „photonic wire bond“



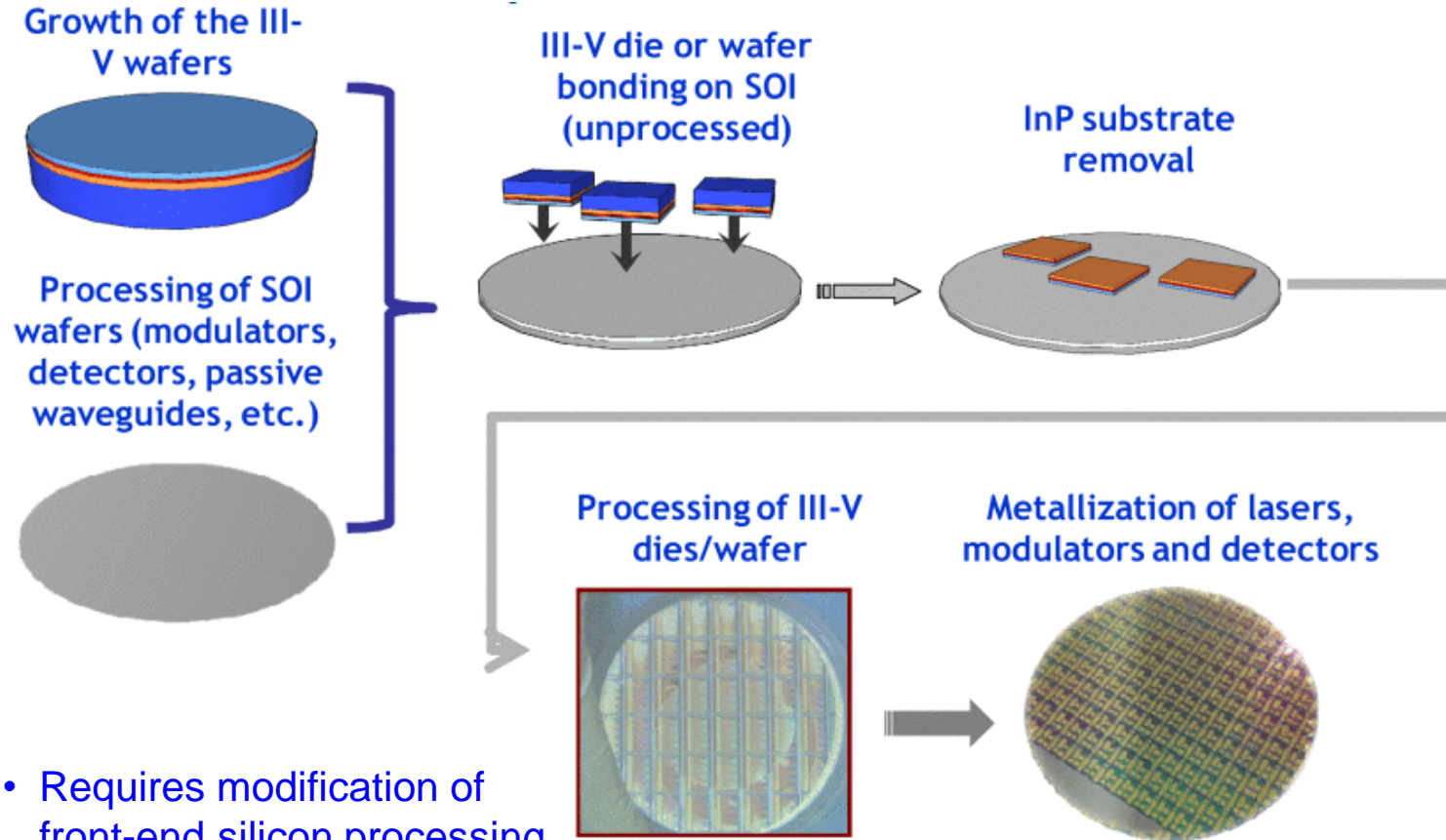
vanguard  
AUTOMATION  
bright connections

**Booth 5718**

- Mounting of chips side-by-side (simplifies heat-sinking of laser)
- No active alignment required

Billah *et al.*, *Optica* **5**, 876-883 (2018)

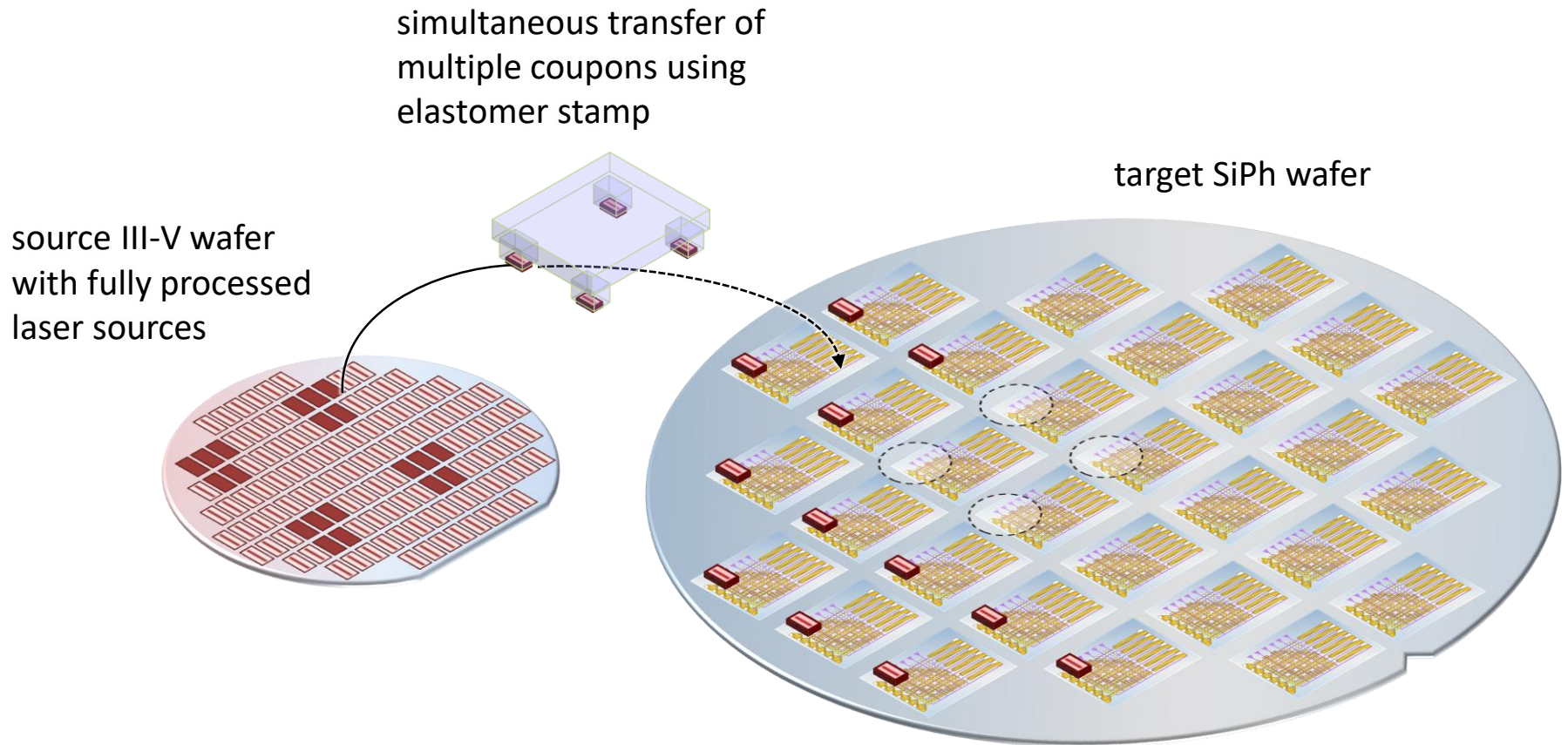
# Die-to-wafer bonding of III-V-materials



- Requires modification of front-end silicon processing
- Performance comparable to native III-V-lasers / amplifiers
- Well suited for narrow-linewidth “external-cavity” lasers with high-Q resonator on silicon chip
- Used commercially, e.g., by Intel, Juniper Networks (former Aurrion) ....

Fang *et al.*, Opt. Express **14**, 9203–9210 (2006)  
Campenhout *et al.*, Opt Express **15**, 6744–6749, (2007)  
Roelkens *et al.*, Laser Photonics Rev. **4** (2010)  
Duan *et al.*, IEEE J. Sel. Top. Quant. Elect.. **20**, 158–170 (2014)  
Roelkens *et al.*, Photonics **2**, 969–1004, 2015.

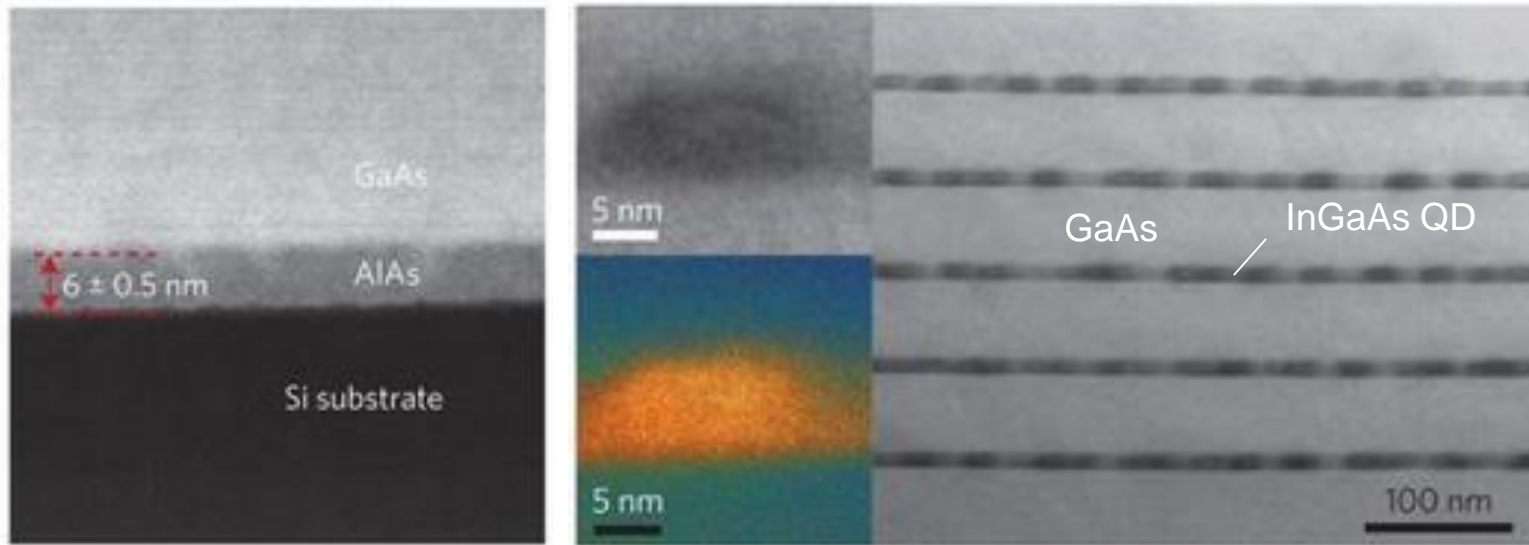
# MICRO-TRANSFER-PRINTING



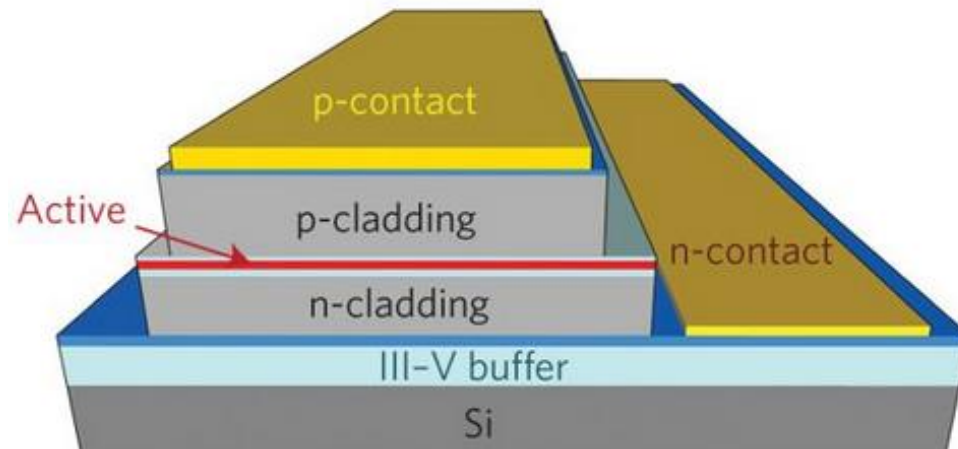
$\mu$ TP combines advantages of flip-chip and die-to-wafer bonding



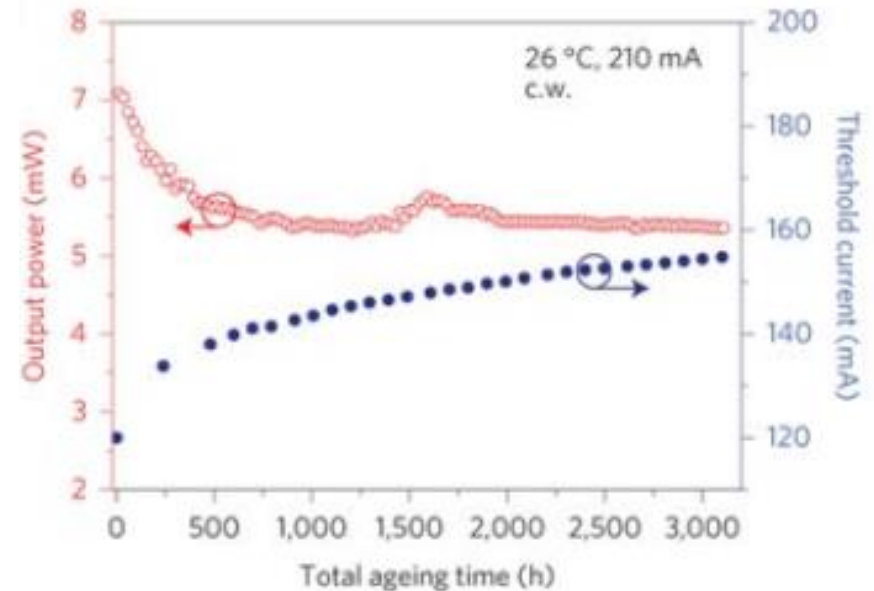
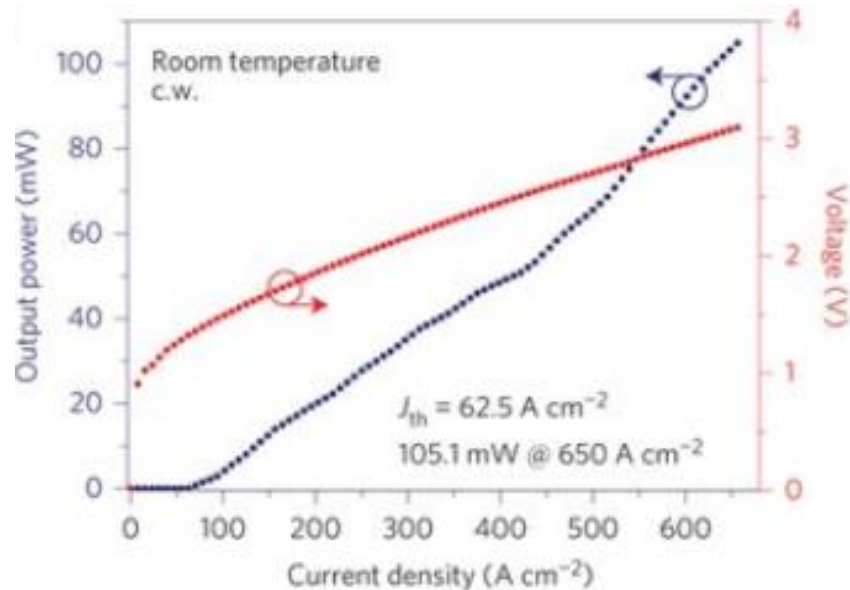
# Epitaxial growth of III-V quantum dots (QD) on Si



- 5 layers InGaAs/GaAs QD, grown on AlAs nucleation layer in Si
- Device fabricated by etching, metallization, cleaving



Chen *et al.*, *Nat. Photonics*, **10** (2016)



**Status:** Strong performance parameters:

- Threshold current density  $< 100 \text{ A/cm}^2$
- Output power  $> 100 \text{ mW}$
- Operation up to  $75^\circ \text{ C}$
- Stable operation for  $> 3000\text{h}$  at  $210 \text{ mA}$

**Challenge:** Integration of MBE growth into CMOS front-end processing

Chen *et al.*, *Nat. Photonics*, **10** (2016)

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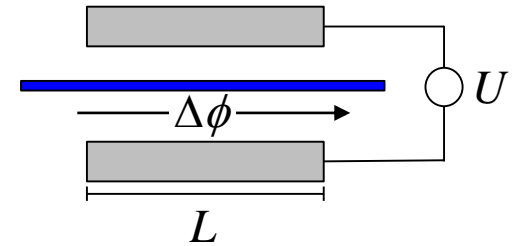
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**$\pi$ -voltage:** Voltage required for a phase shift of  $\Delta\Phi = \pi$

$$(1) \quad \Delta\phi = k_0 \Delta n_e L = \pi \frac{U}{U_\pi} \quad \text{for} \quad \Delta n_e \propto U \quad [U_\pi] = 1 \text{ V}$$



**$\pi$ -voltage-length product:** Trade-off between operation voltage and device length

$$(2) \quad \frac{1}{U_\pi L} = \frac{k_0}{\pi} \frac{\Delta n_e}{U} \quad [U_\pi L] = 1 \text{ Vmm}$$

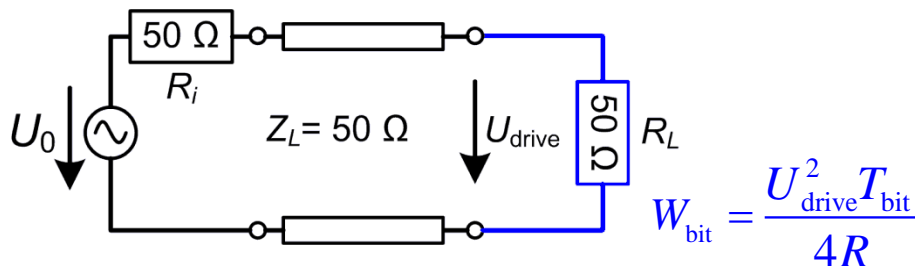
**Voltage-loss product:** Trade-off between operation voltage and optical insertion loss

$$(3) \quad a_{\text{dB}} = -10 \log(e^{-\alpha L}) \approx 4.34 \alpha L \quad a_{\text{dB}} U_\pi = \frac{4.34 \alpha}{k_0 \frac{\Delta n_e}{\pi U}} \quad [\alpha] = 1 / \text{m}$$

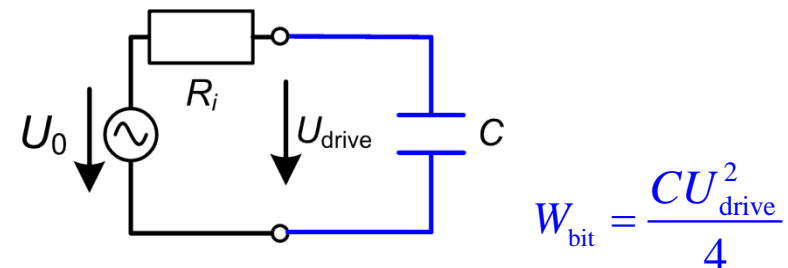
$$[a_{\text{dB}} U_\pi] = 1 \text{ V dB}$$

**Power dissipation:**

**Travelling-wave modulator:**



**Lumped-element (capacitive load):**



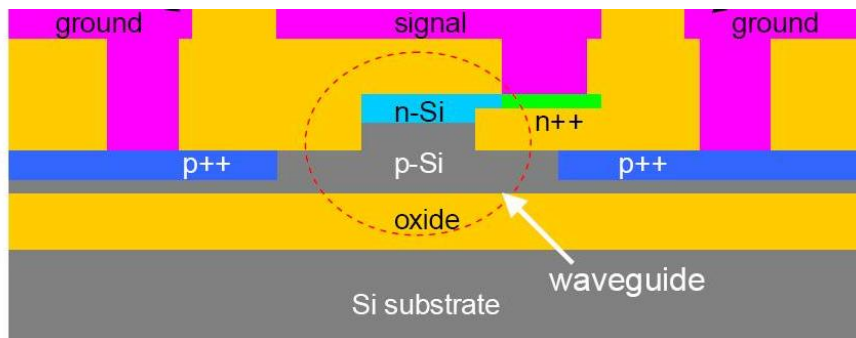
- Refractive index change induced by injection/removal of free electrons and holes

$$\Delta n = -(e^2 \lambda^2 / 8 \pi^2 c^2 \epsilon_0 n) [\Delta N_e / m_{ce}^* + \Delta N_h / m_{ch}^*]$$

$$\Delta \alpha = (e^3 \lambda^2 / 4 \pi^2 c^3 \epsilon_0 n) [\Delta N_e / m_{ce}^{*2} \mu_e + \Delta N_h / m_{ch}^{*2} \mu_h]$$

Soref *et al.*, IEEE J. Quantum Electron. **23**, 123–129, (1987)

- Carrier density modulation by depletion in reverse biased p-n-junctions or by carrier accumulation in silicon–insulator–silicon capacitors (SISCAP)

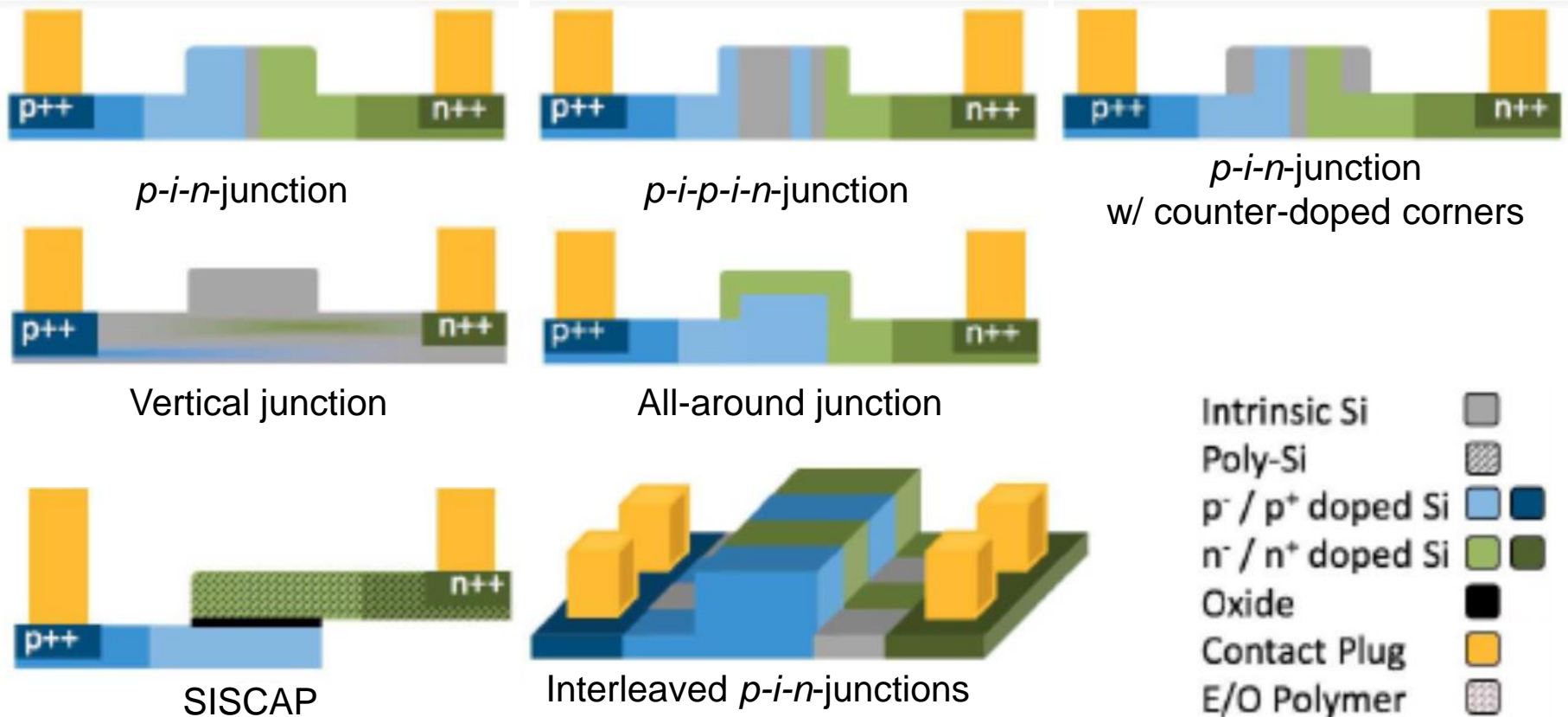


Liao *et al.*, Electron. Lett. 43, 1196 – 1197 (2007)  
Liu *et al.*, Opt. Express 15, 660 – 668 (2007)

Depletion-layer width: 
$$l = \sqrt{\frac{2 \epsilon_r \epsilon_0}{e} (U_D - U) \left( \frac{1}{n_A} + \frac{1}{n_D} \right)} \quad U_D = U_T \ln \left( \frac{n_A n_D}{n_i^2} \right)$$

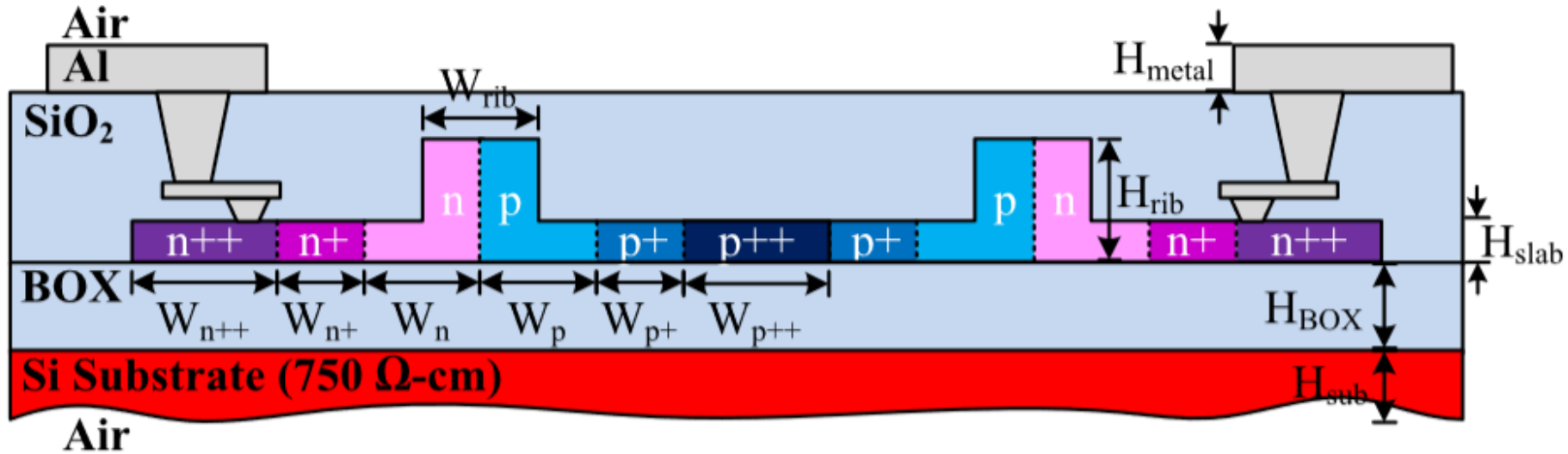
# All-silicon modulators phase shifters: Design principles

- Place carriers where they get dynamically depleted and actively contribute to index modulation
- Reduce carrier density elsewhere to the minimum required to ensure low RC time constant
- **Note:** Small device capacitance reduces  $U_{\pi}L$ , but increases RC time constant

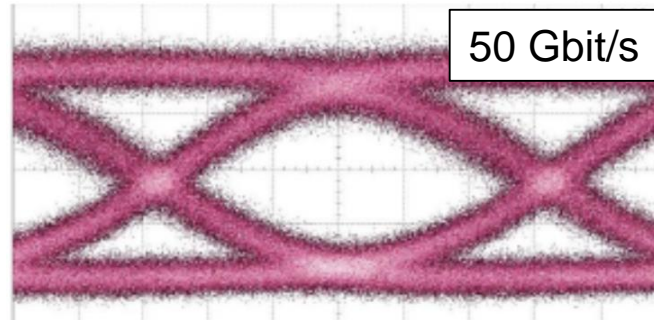


Witzens, IEEE Proc. **106**, 2158 – 2182 (2018)

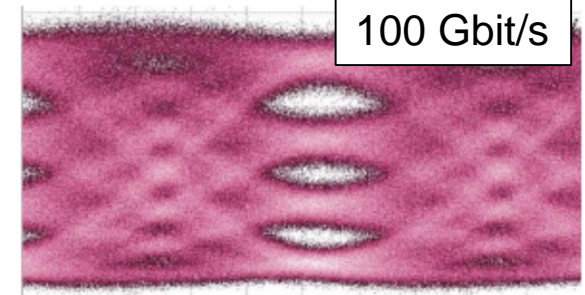
# Examples of all-silicon modulators



Reverse-biased p-n-junction: Small capacitance, high bandwidth



50 Gbit/s

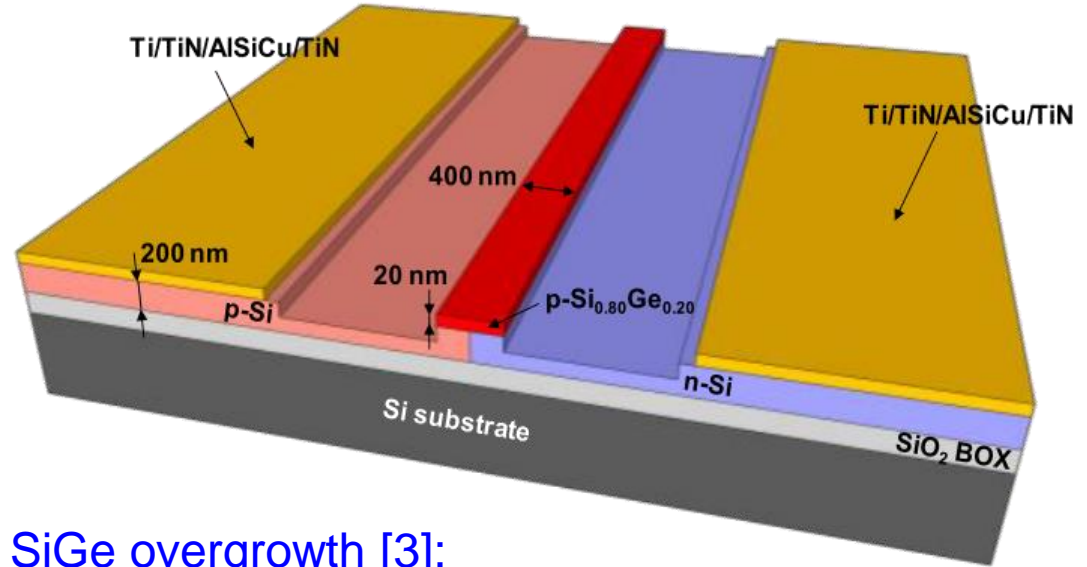
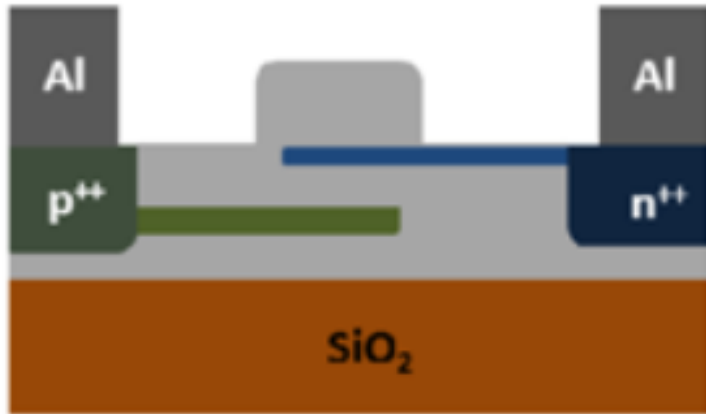


100 Gbit/s

Technology		BW	$U_{\pi}L$	$\alpha_{dB} U_{\pi}$
pn-type	[1]	50 GHz	25 Vmm	NA

[1] Patel *et al.*, Photon. Technol. Lett. **27**, 2015

# Examples of all-silicon modulators



## Vertical pn-junction [2]:

- Larger depletion volume, higher capacitance
- High doping to maintain bandwidth

## SiGe overgrowth [3]:

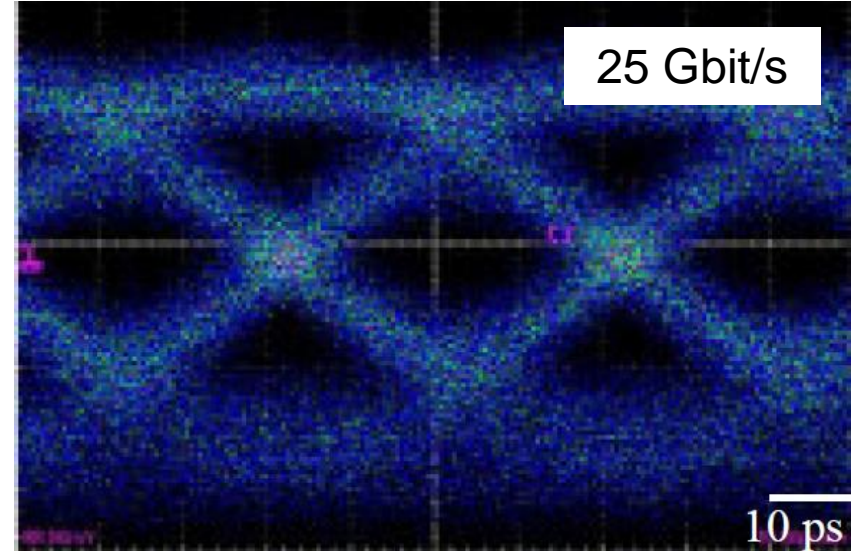
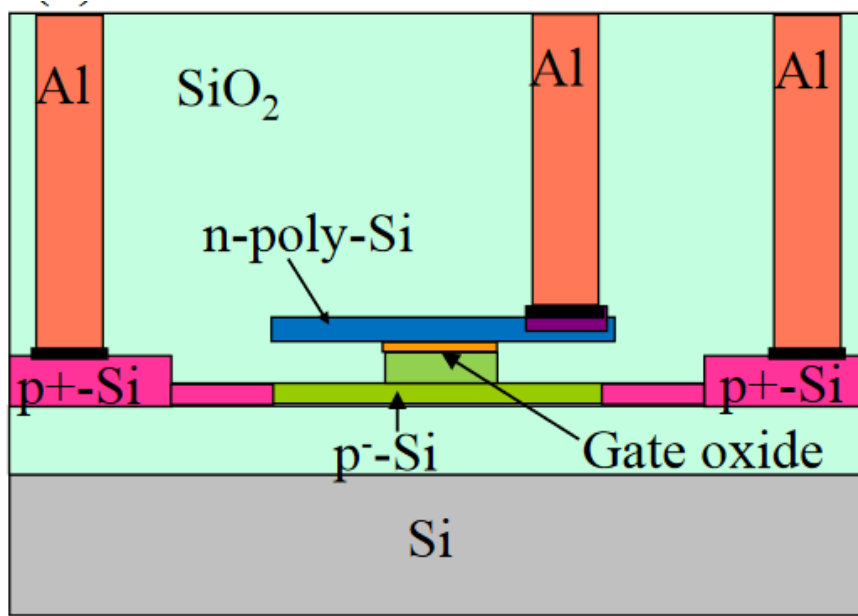
- Large depletion volume
- Strain leads to reduction of the hole effective mass, enhancing the change of refractive index and absorption

Technology/FOM		BW	$U_{\pi}L$	$a_{dB}U_{\pi}$
pn-type (vertical)	[2]	48 GHz	7.4 Vmm	31 V dB
pn-type (SiGe)	[3]	~ 10 GHz	6 Vmm	12 V dB

[2] Azadeh *et al.*, Opt. Express **23**, 23526 (2015)

[3] Fujikata *et al.*, ECOC 2016, Tu.3.A.4





- Operated in accumulation mode.
- Weak doping allows to reduce losses.
- High capacitance leads to high efficiency, but increases RC time constant.

Technology		BW	$U_{\pi}L$	$a_{dB}U_{\pi}$
SISCAP	[4]	< 20 GHz	1.6 Vmm	5.6 V dB

[4] Fujikata *et al.*, Jpn. J. Appl. Phys. **55**, 2016

# Hybrid modulators: III-V on silicon

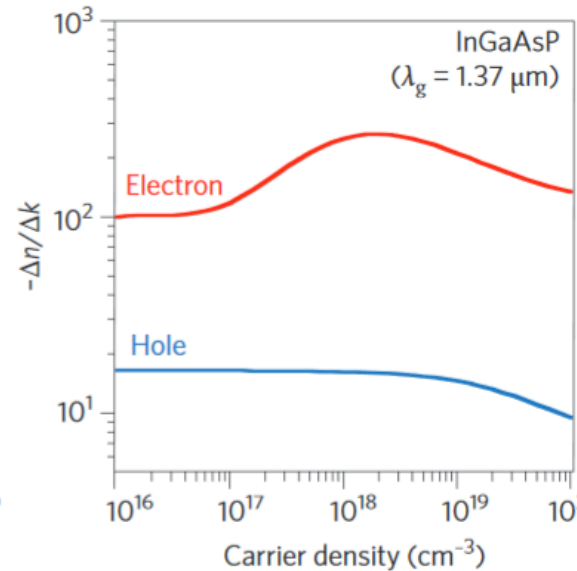
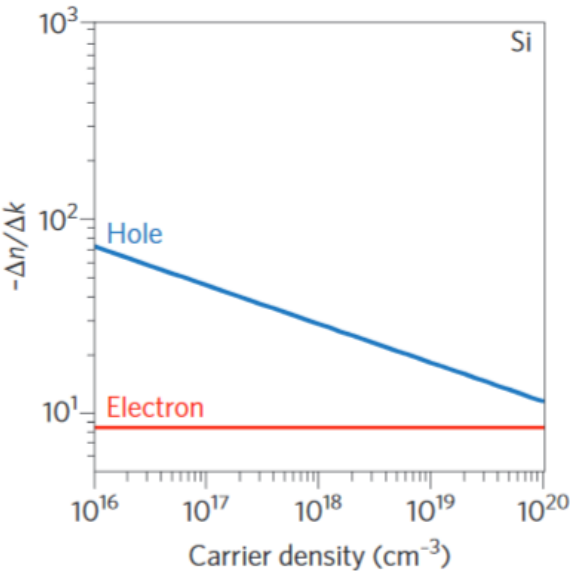
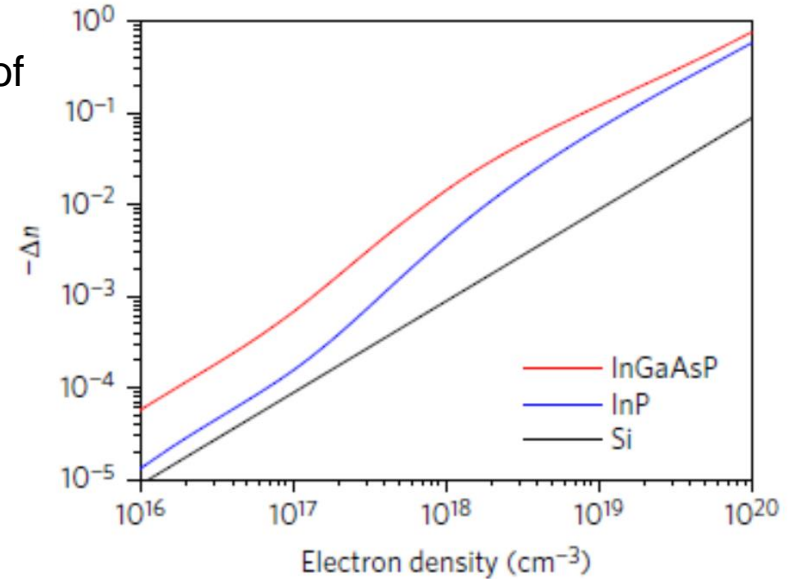
Magnitude of **carrier-induced refraction  $\Delta n$**  and **absorption  $\Delta k$**  depends on effective mass and mobility of the respective carrier type.

## InGaAsP: Electrons favoured

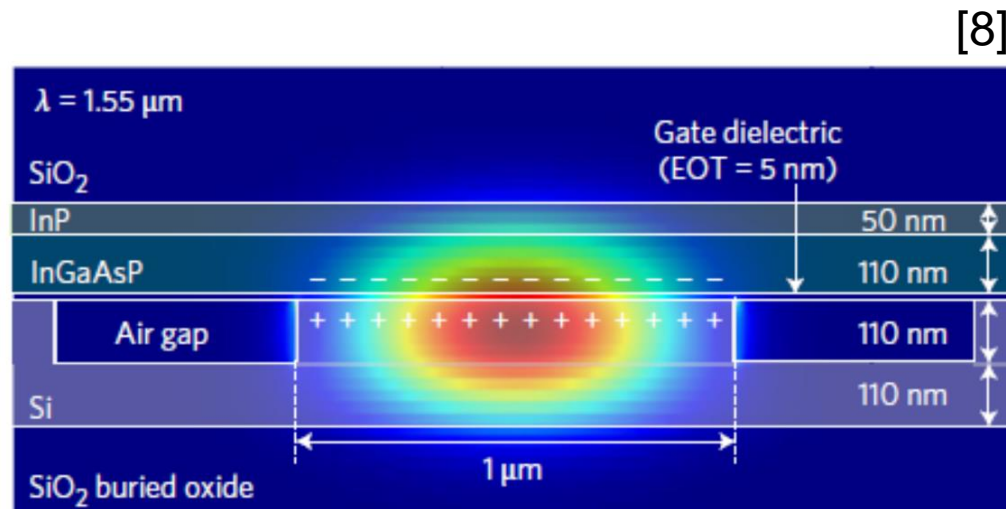
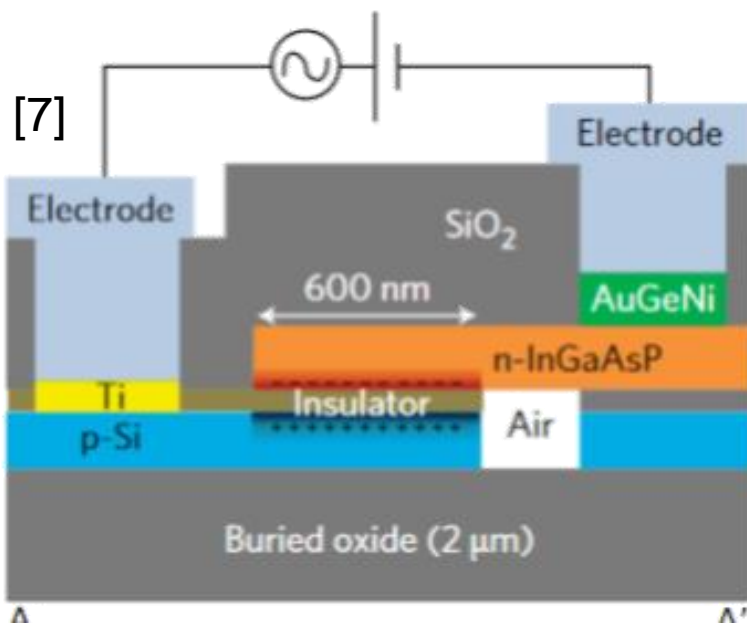
- Stronger contribution  $\Delta n$  to refractive index than in Si
- Stronger relative contribution  $\Delta n/\Delta k$

**Silicon: Holes favoured** due to stronger relative contribution  $\Delta n/\Delta k$

⇒ Ideal: SISCAP structure with electrons in InGaAsP and holes in Si



Witzens, Nature Photon. **11**, 459 (2017)  
 Hiraki *et al.*, Nature Photon. **11**, 482, (2017)  
 Han *et al.*, Nature Photon. **11**, 486, (2017)



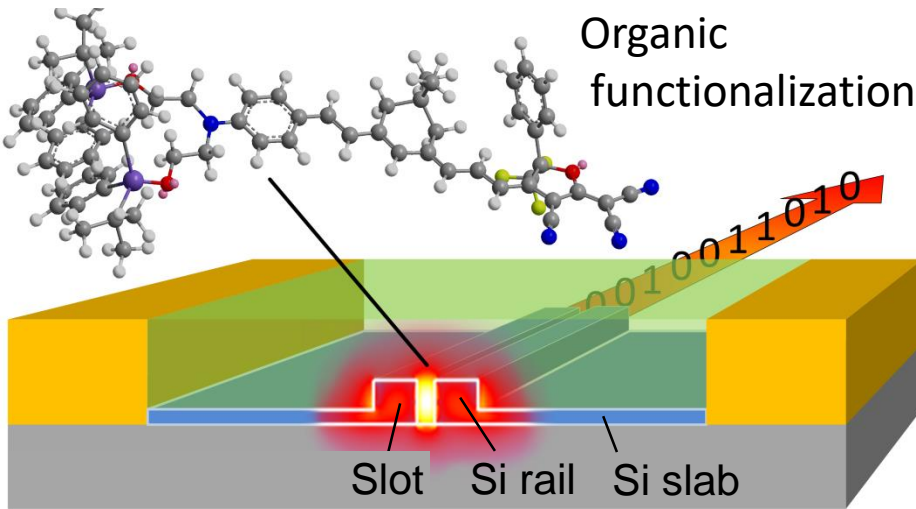
Technology		BW	$U_{\pi}L$	$a_{dB}U_{\pi}$
III-V on Si	[5]	2.2 GHz*	0.9 Vmm	4 V dB
III-V on Si	[6]	100 MHz*	0.47 Vmm	0.9 V dB

[5] Hiraki *et al.*, Nature Photon. **11**, 482, 2017

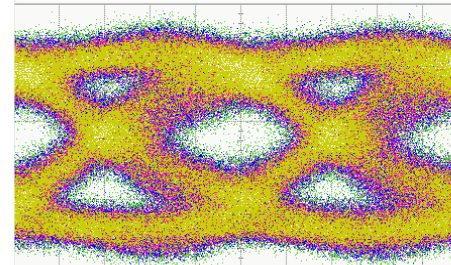
[6] Han *et al.*, Nature Photon. **11**, 486, 2017

\* Currently limited by contact resistance (not fundamental!)

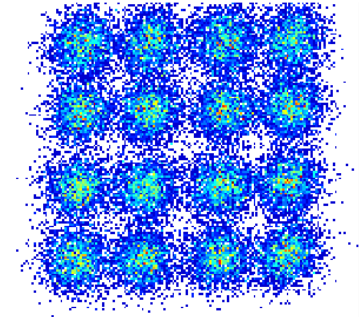
# Silicon-Organic Hybrid (SOH) Electro-Optic Modulators



100 Gbit/s OOK

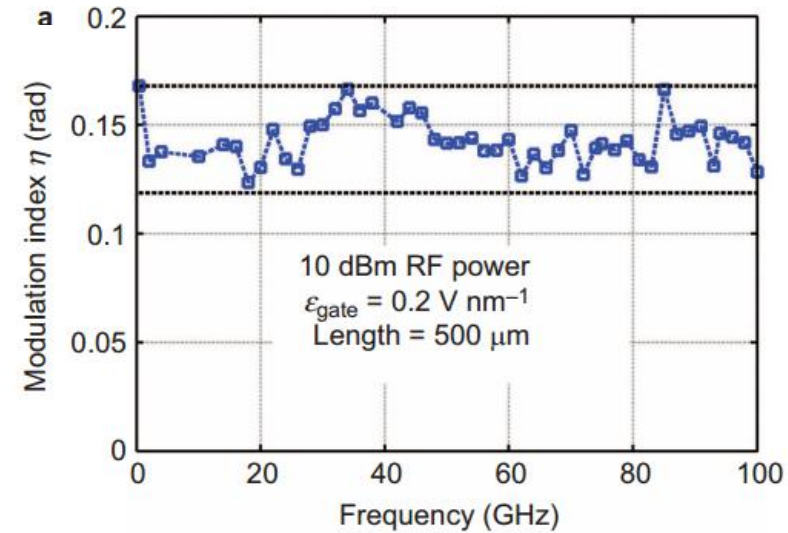


100 GBd 16 QAM



- **Concept:** Combine silicon-on-insulator waveguides with organic electro-optic cladding material
- **Highly efficient materials obtained by theory-guided molecular design:**  $r_{33} = 390 \text{ pm/V}$ ,  $U_{\pi}L \approx 0.3 \text{ Vmm}$
- **Can be realized by back-end-of-line processing**

		BW	$U_{\pi}L$	$a_{\text{dB}}U_{\pi}$
SOH	[10]	20 GHz	<b>0.32 Vmm</b>	<b>1.2 V dB</b>



[8] Koos *et al.*, J. Lightw. Technol. **24**, 256-268 (2016)

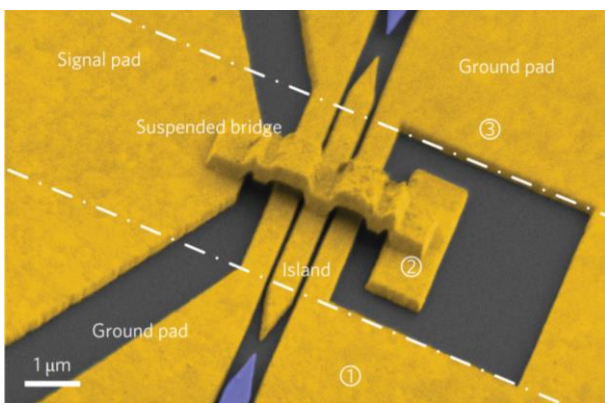
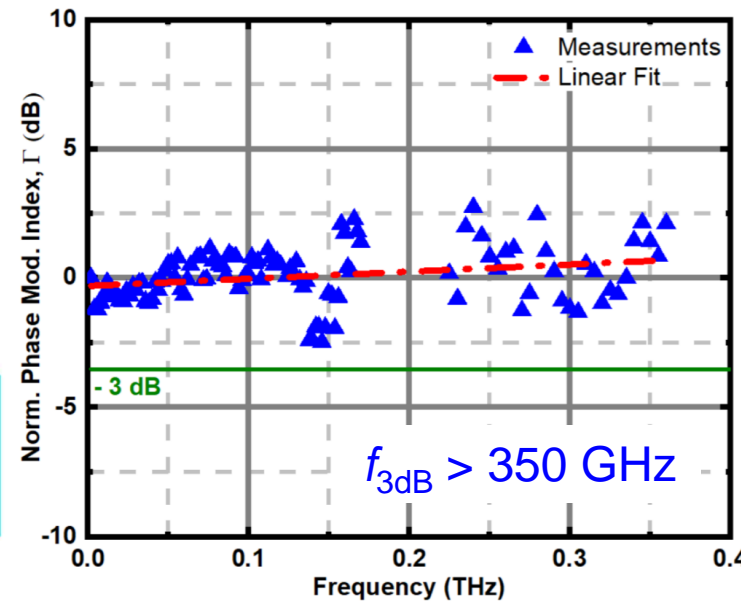
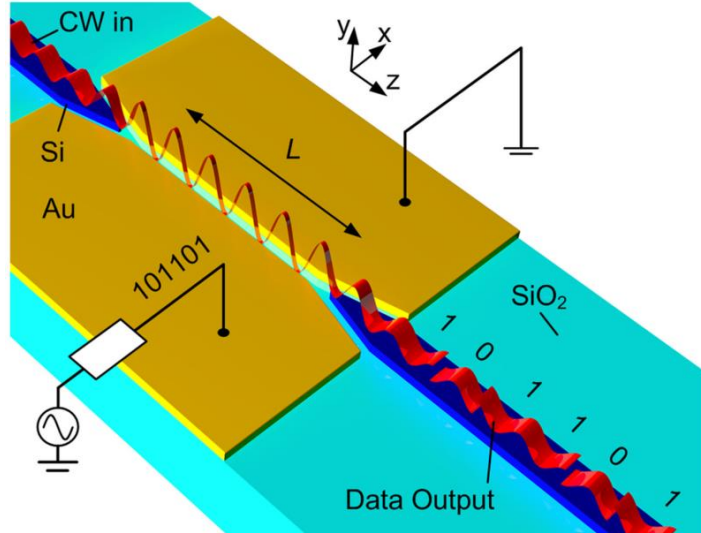
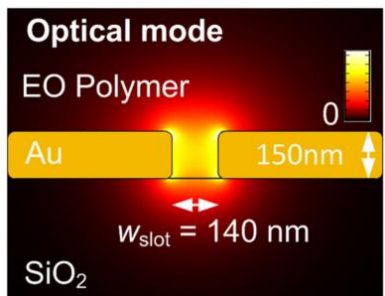
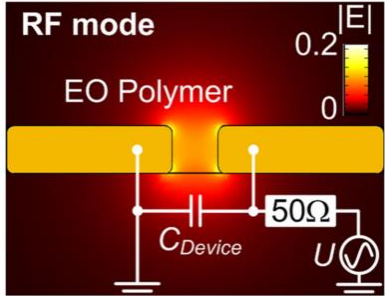
[9] Alloatti *et al.*, Light Sci. Appl. **3** (2014)

[10] Kieninger *et al.*, Optica **5**, 739 - 748 (2018)

[11] Wolf *et al.*, Opt. Express **26**, 220-232 (2018)

[12] Wolf *et al.*, Scientific Reports **8**, 2598-1 – 2598-13 (2018)

# Plasmonic-organic hybrid (POH) modulators



Technology	Ref	BW	$U_{\pi}L$	$a_{dB}U_{\pi}$
POH	[12]	> 70 GHz	0.06 Vmm	96 V dB
POH	[13]	NA	0.05 Vmm	22 V dB
POH	[14]	> 170 GHz	~0.1Vmm	~30 V dB

[11] Melikyan et al. *Nature Photonics* **8** (3) p 229 (2014)  
 [12] Haffner, C. et al. *Nature Photonics* **9** (8) p 525 (2015)

[13] Heni W. et al. *Optics Express* **25** (3) p 2627 (2017)  
 [14] Hoessbacher et al., *Opt. Express* **25**, 1762 (2017)  
 [15] Ummethala S. et al., *Cleo 2018*, paper STu3D.4

# Overview: Performance of hybrid and all-silicon modulators

Technology		BW	$U_{\pi}L$	$a_{\text{dB}}U_{\pi}$	Process modifications beyond standard silicon photonics
pn-type	[1]	50 GHz	25 Vmm	NA	None
pn-type (vertical)	[2]	48 GHz	7.4 Vmm	31 V dB	None
pn-type (SiGe)	[3]	~ 10 GHz	6 Vmm	12 V dB	None
SISCAP	[4]	< 20 GHz	1.6 Vmm	5.6 V dB	None
SOH	[9]	100 GHz	11 Vmm	55 V dB	BEOL post-processing
SOH	[10]	20 GHz	0.32 Vmm	1.2 V dB	BEOL post-processing
III-V on Si	[5]	2.2 GHz	0.9 Vmm	4 V dB	New process
III-V on Si	[6]	0.2 GHz	0.47 Vmm	0.9 V dB	New process
POH	[12]	> 70 GHz	0.06 Vmm	96 V dB	New process
POH	[13]	NA	0.05 Vmm	22 V dB	New process
POH	[14]	> 170 GHz	~0.1 Vmm	~30 V dB	New process
Si-BTO	[7]	30 GHz	4.5 Vmm	4.5 V dB	New process
LiNbO <sub>3</sub> on Si	[16]	100 GHz	22 Vmm	0.44 V dB	New process

[7] Abel *et al.*, Nature Materials **18**, 42 (2019)

[16] Wang *et al.*, Nature **562**, 101-104, 2018

## Introduction

- Scalability challenges in optical communications
- Silicon photonics and the need for hybrid integration

## Silicon-based building blocks for high-bandwidth transceivers

- Waveguides and passive devices
- Photodetectors
- Light sources
- Modulators

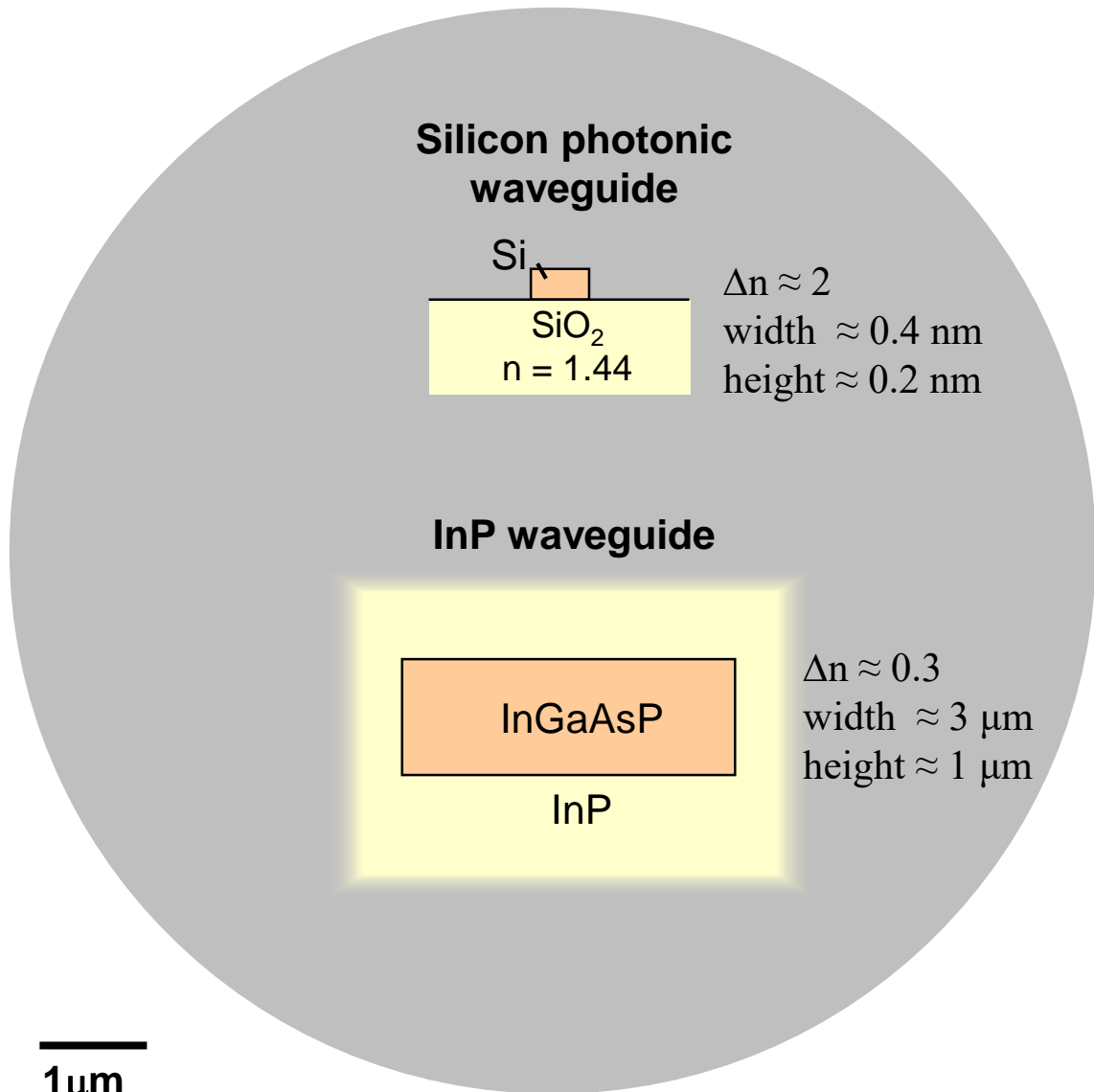
## Packaging and system assembly

- Coupling interfaces to silicon photonic waveguides
- In-situ waveguide fabrication by 3D laser lithography

## Silicon photonic transceivers

- Commercial products and experimental demonstrations
- Towards massively parallel WDM transceivers

## Summary



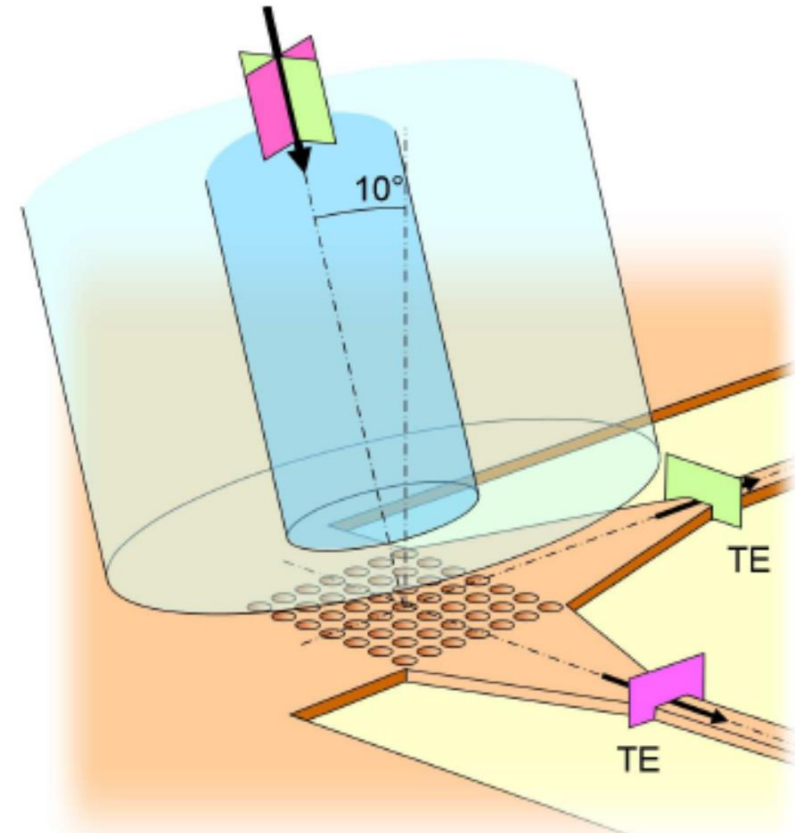
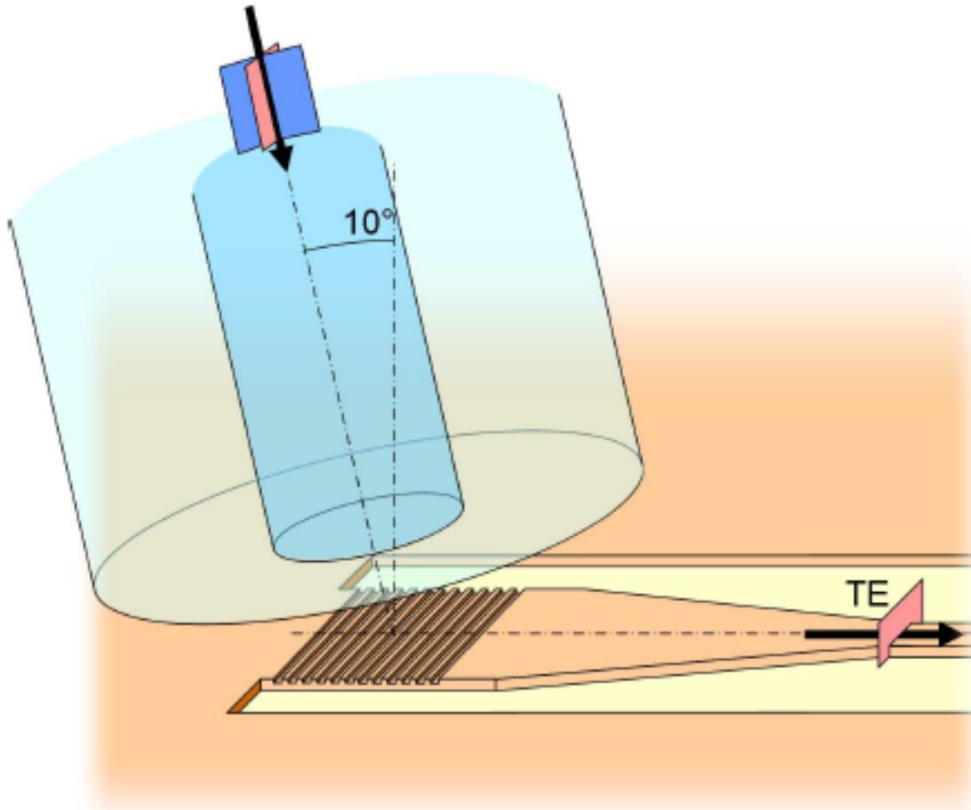
## Challenges:

- Mode matching
- High-precision active alignment
- Polarization handling

## Single-mode fiber core

$$\Delta n \approx 10^{-3}$$
$$\varnothing \approx 10 \text{ }\mu\text{m}$$



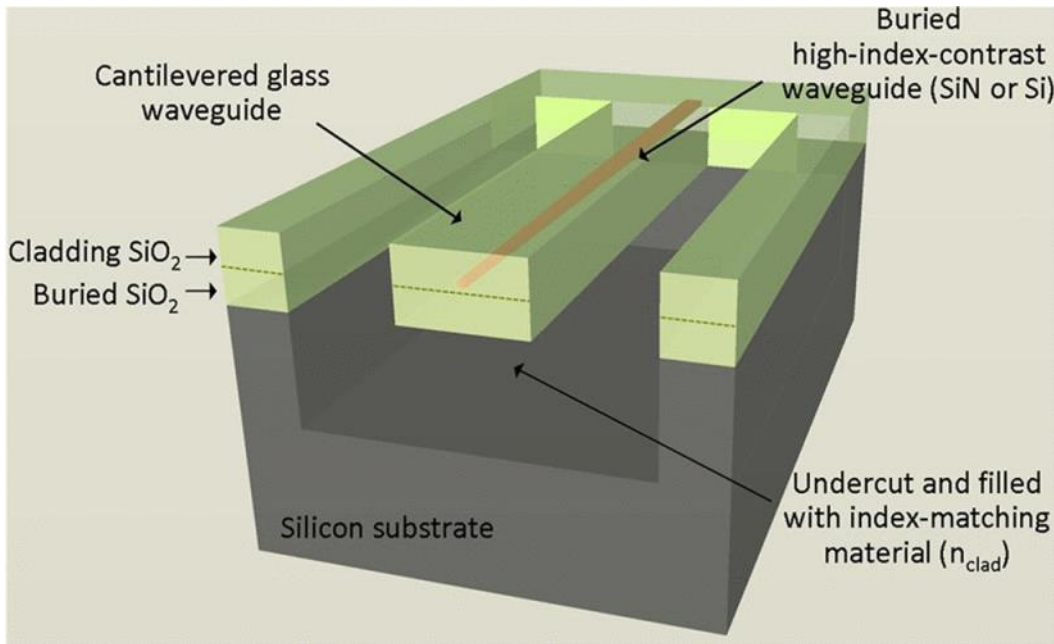


- Chip-level testing
- Coupling loss 0.5 ... 4.5 dB (0.5 dB backside mirror)
- Bandwidth typ. 40 nm
- Single polarization

- Polarization splitting

Bogaerts *et al.*, *Opt. Express* **15**, 1567-1578, (2007)  
Laere *et al.*, *IEEE Photon. Technol. Lett.* **20**, 318-320 (2008)  
Zaoui *et al.*, *IEEE Photon. Technol. Lett.* **25**, 1277-1286 (2013)

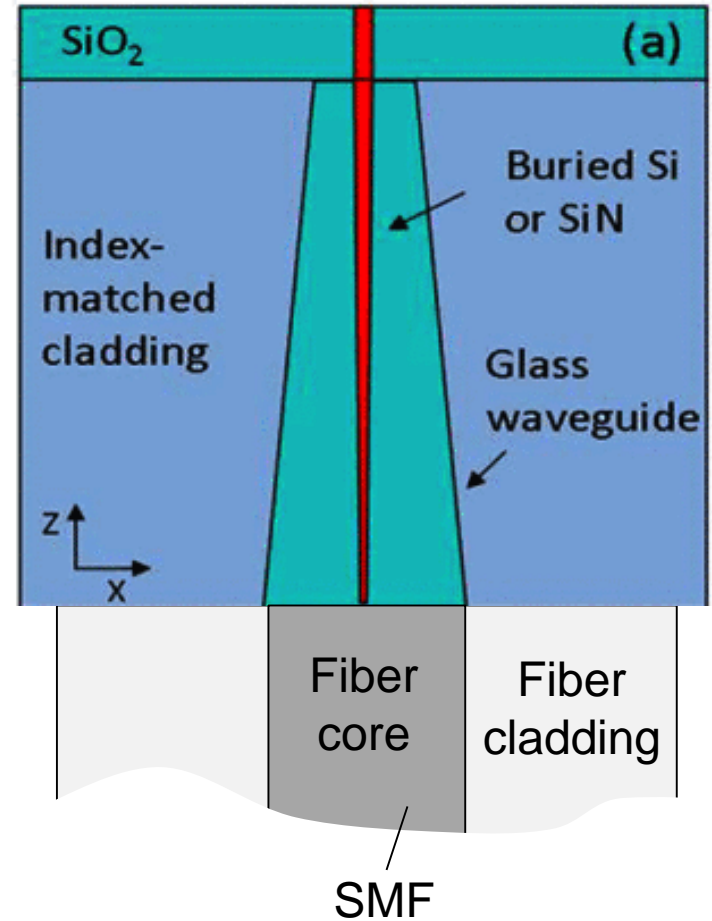
# Edge couplers



- Coupling loss 0.5 ... 2 dB
- Bandwidth 300 nm
- PDL 0.5 dB

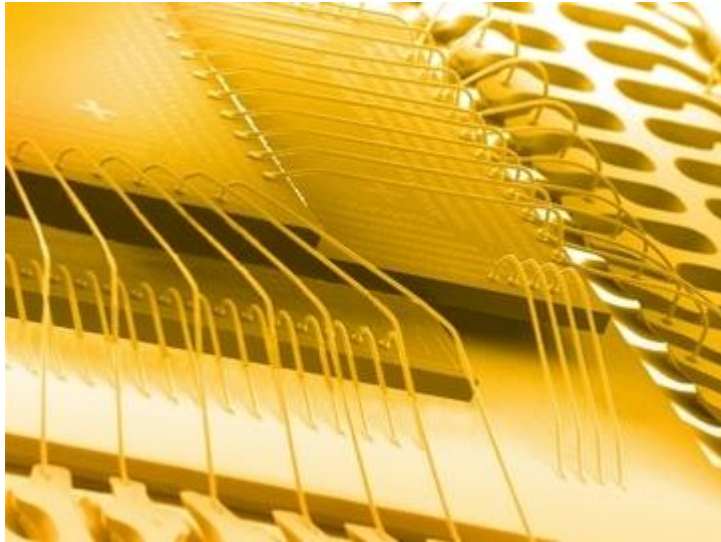
**Note:** System assembly still requires precise (active) alignment

Chen *et al.*, IEEE Photon. Technol. Lett. **22** (2010)  
 Pu, et al., *Opt. Commun.* **283**, 3678–3682, (2010)  
 Fang et al. *Opt. Express* **19**, 21588–21594 (2011)



## Integrated polarization rotators:

Fukuda *et al.*, *Opt. Express* **16**, 2628-2635 (2008)  
 Watts *et al.*, *Opt. Lett.* **30**, 138-140 (2005)  
 Chen et al. *Opt. Lett.* **36**, 469-471 (2011)



## Electronic wire bonding: Stacked-die package

- Highly scalable automated fabrication (10's of connections per second)
- Tight control of the loop trajectory

Picture source: Kulicke & Soffa, <http://www.kns.com/>

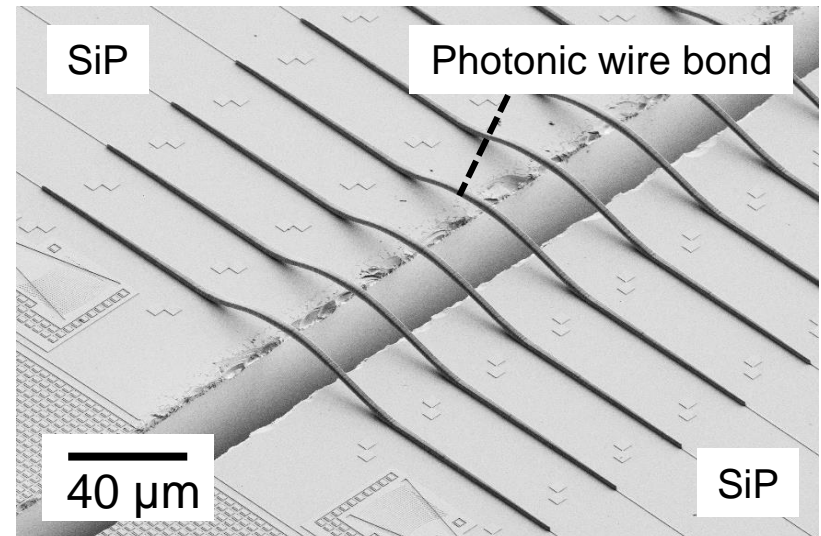
## Photonic wire bonding: Replace metallic wire by a 3D freeform polymer waveguide

- No high-precision/active alignment required
- Can connect to arbitrary mode fields
- High interconnect density
- Automated fabrication

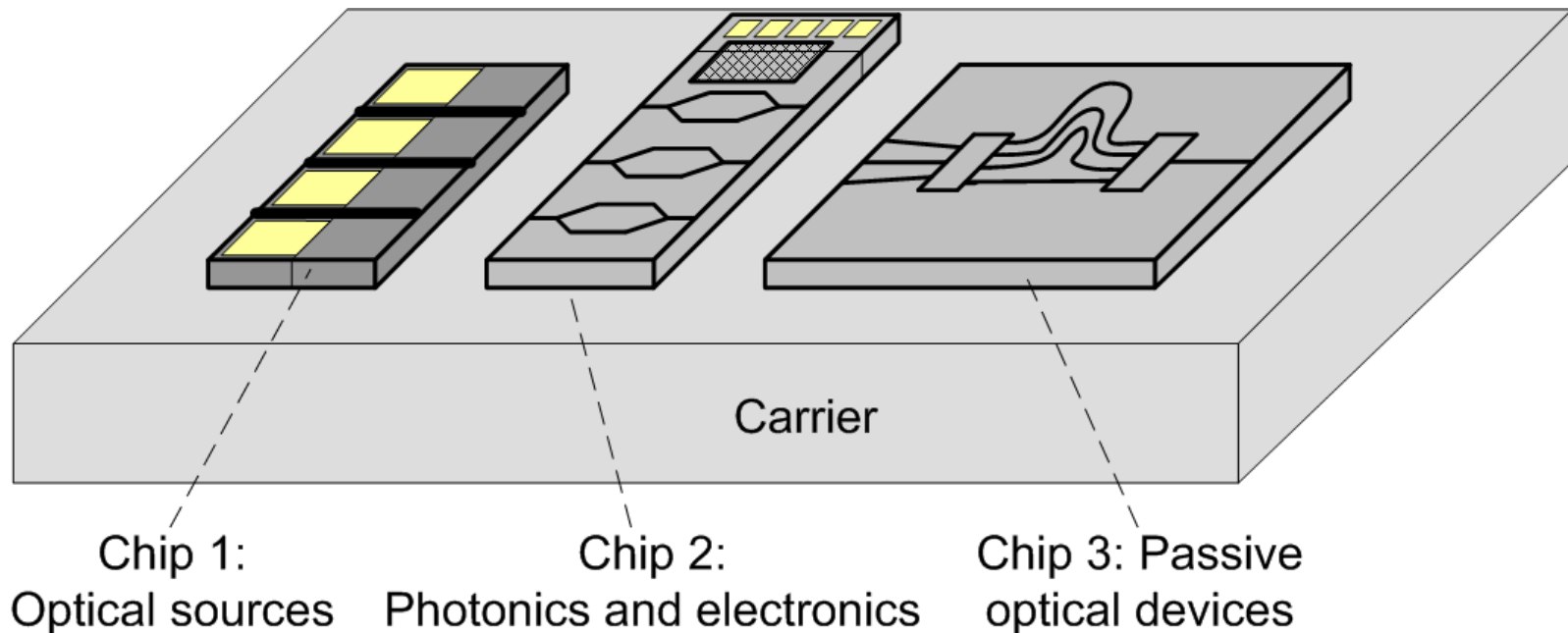
Lindenmann *et al.*, *Opt. Express* **20**, 17667-17677 (2012)

Lindenmann *et al.*, *J. Light. Technol.* **33**, 755-760 (2015)

Billah *et al.*, *Optica* **5**, 876-883 (2018)



# Photonic wire bonding: The concept

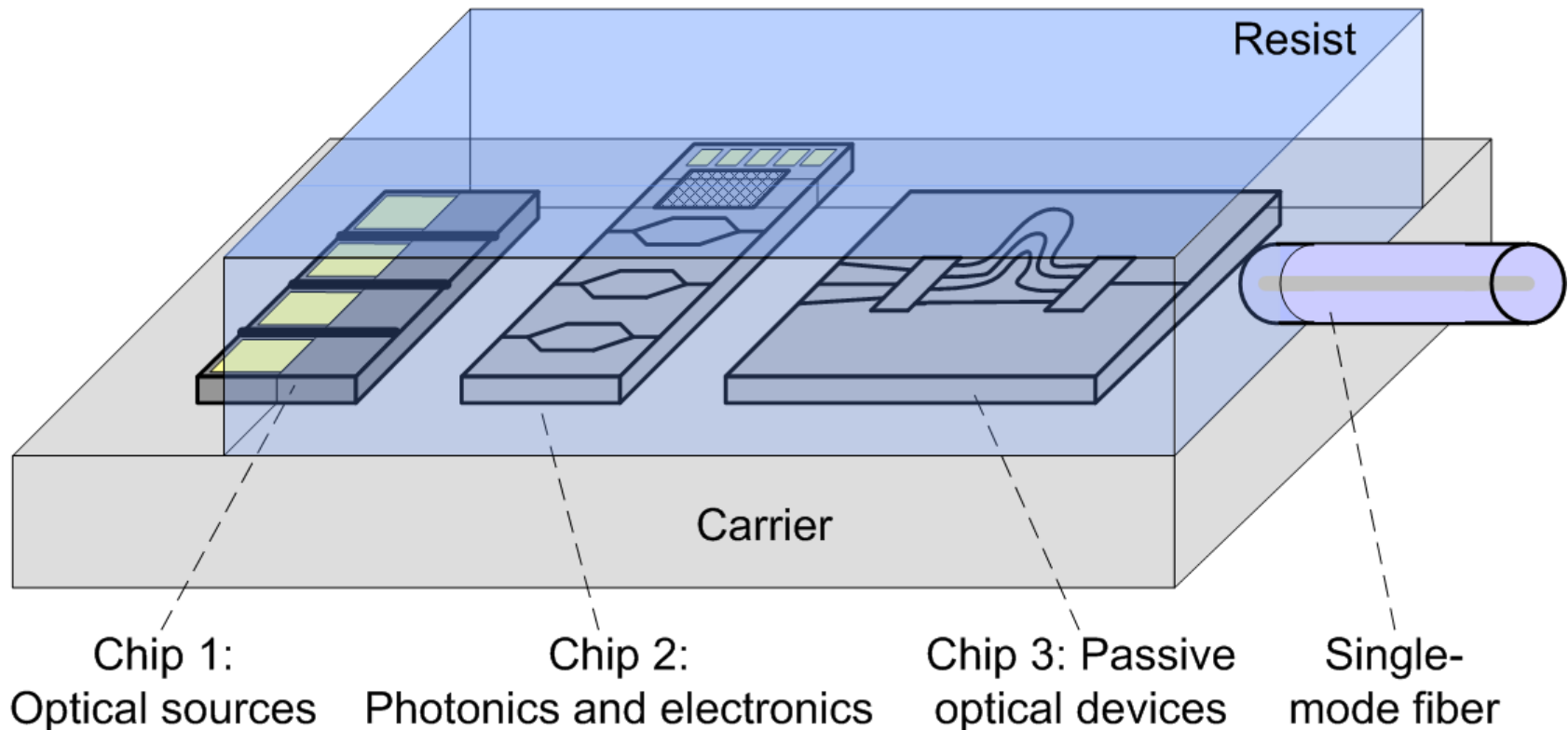


Lindenmann *et al.*, *Opt. Express* **20**, 17667-17677 (2012)

Lindenmann *et al.*, *J. Light. Technol.* **33**, 755-760 (2015)

Billah *et al.*, *Optica* **5**, 876-883(2018)

# Photonic wire bonding: The concept

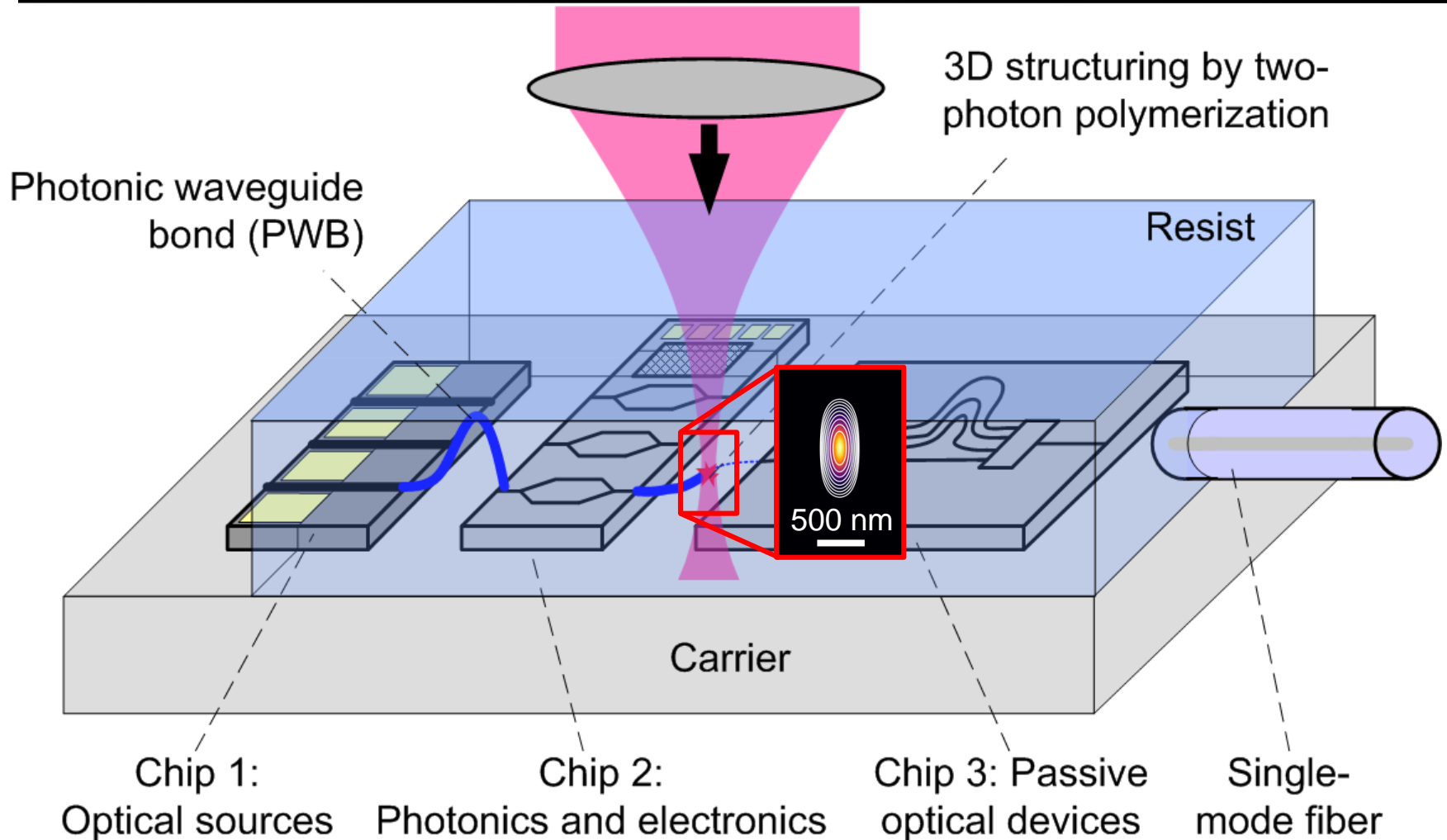


Lindenmann *et al.*, Opt. Express **20**, 17667-17677 (2012)

Lindenmann *et al.*, J. Light. Technol. **33**, 755-760 (2015)

Billah *et al.*, Optica **5**, 876-883(2018)

# Photonic wire bonding: The concept



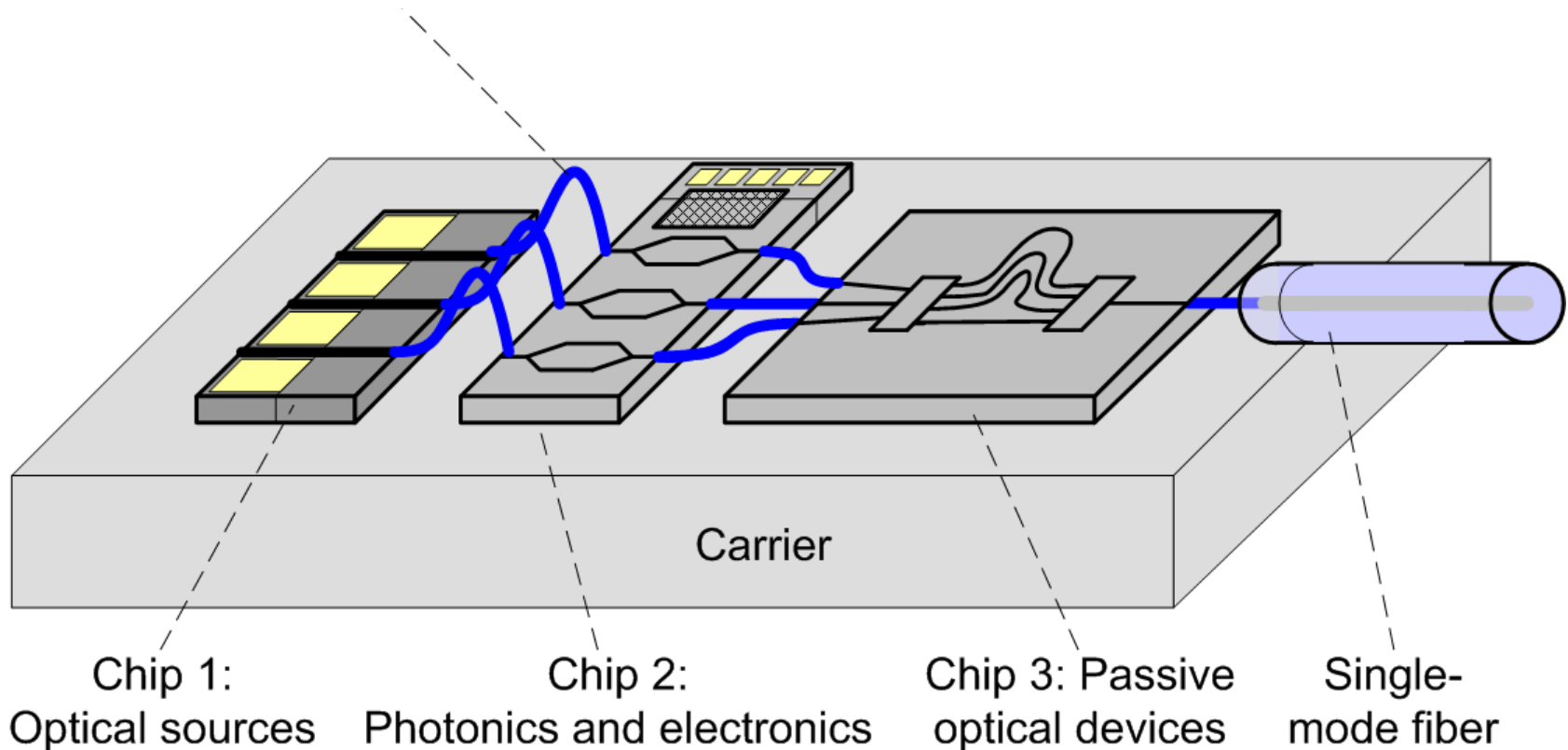
Lindenmann *et al.*, *Opt. Express* **20**, 17667-17677 (2012)

Lindenmann *et al.*, *J. Light. Technol.* **33**, 755-760 (2015)

Billah *et al.*, *Optica* **5**, 876-883(2018)

# Photonic wire bonding: The concept

## Photonic wire bond (PWB)

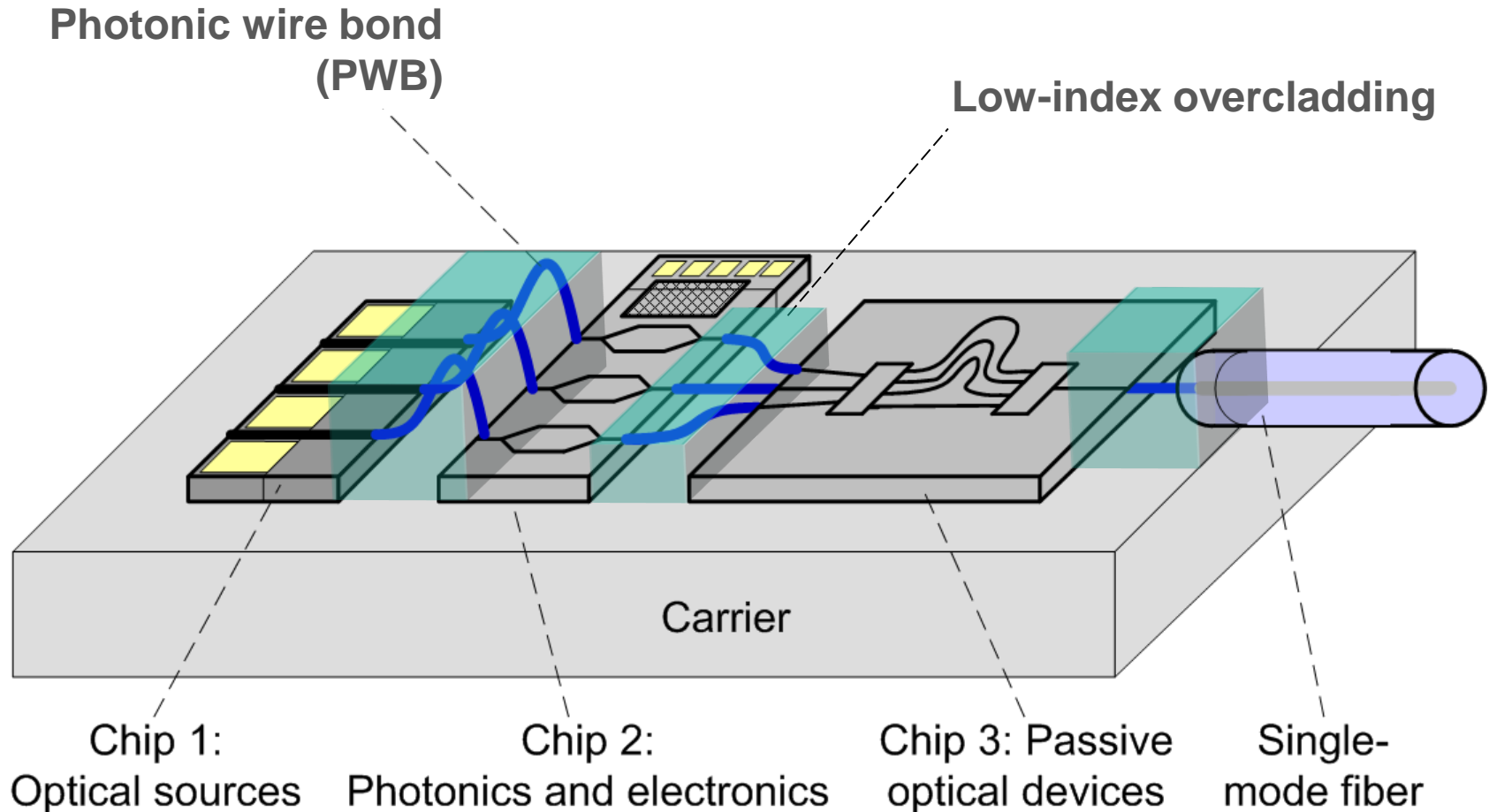


Lindenmann *et al.*, *Opt. Express* **20**, 17667-17677 (2012)

Lindenmann *et al.*, *J. Light. Technol.* **33**, 755-760 (2015)

Billah *et al.*, *Optica* **5**, 876-883(2018)

# Photonic wire bonding: The concept



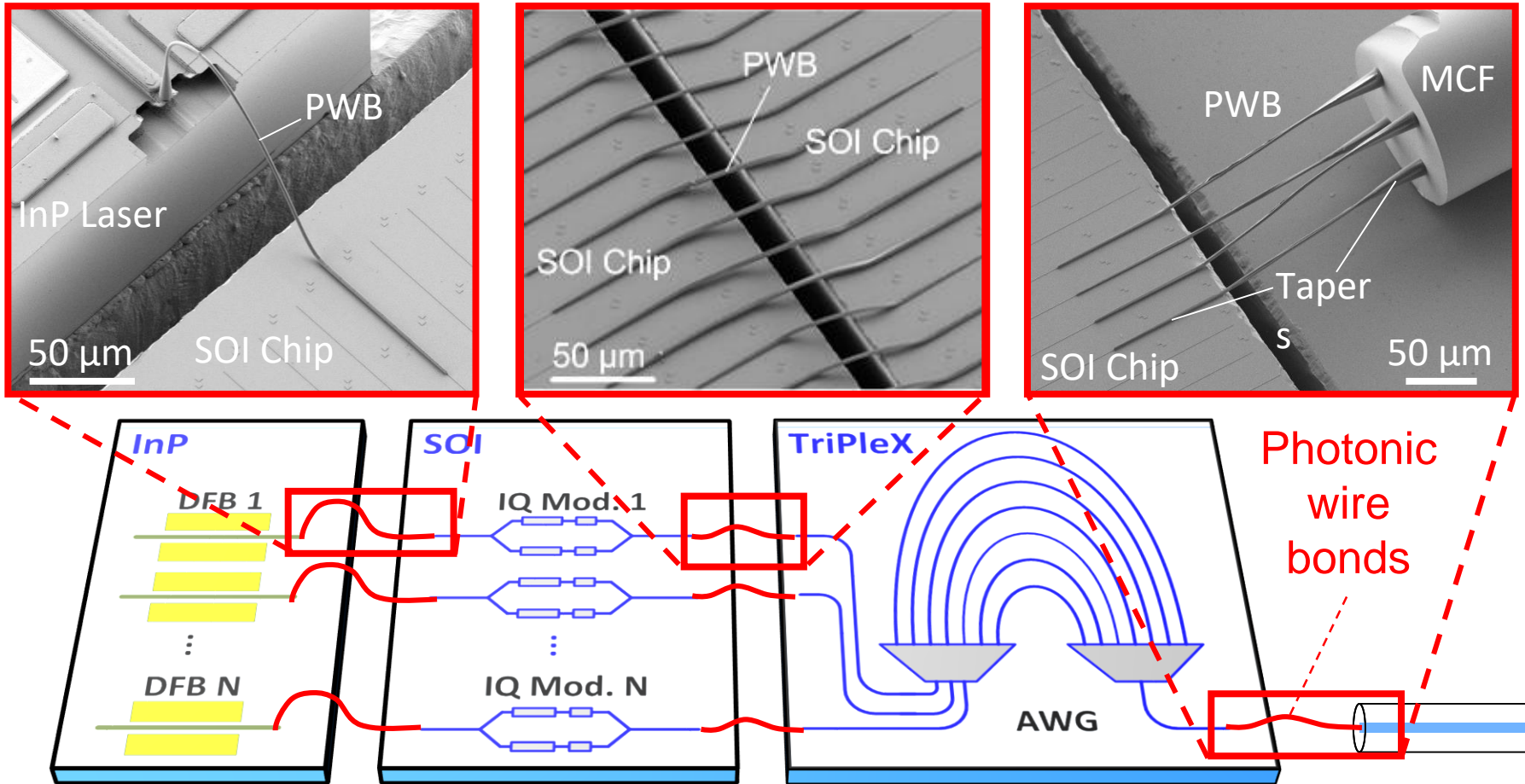
Lindenmann *et al.*, *Opt. Express* **20**, 17667-17677 (2012)

Lindenmann *et al.*, *J. Light. Technol.* **33**, 755-760 (2015)

Billah *et al.*, *Optica* **5**, 876-883(2018)

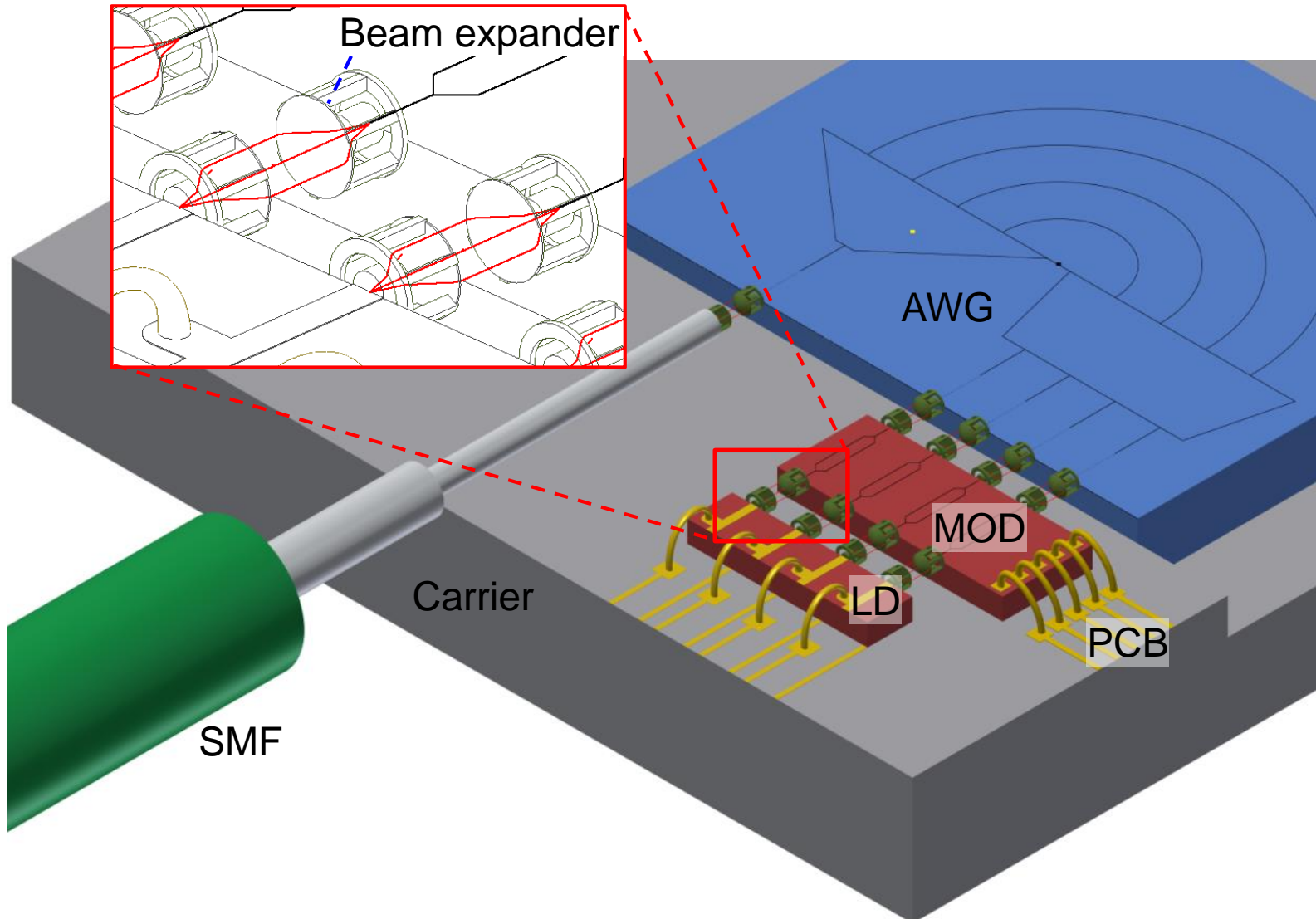


# Example: Optical WDM transmitter module



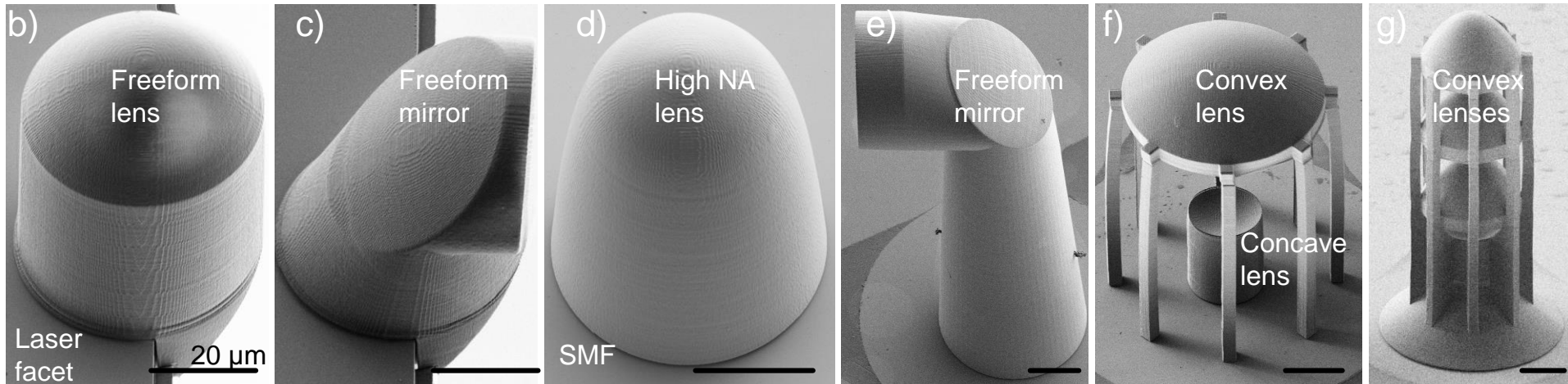
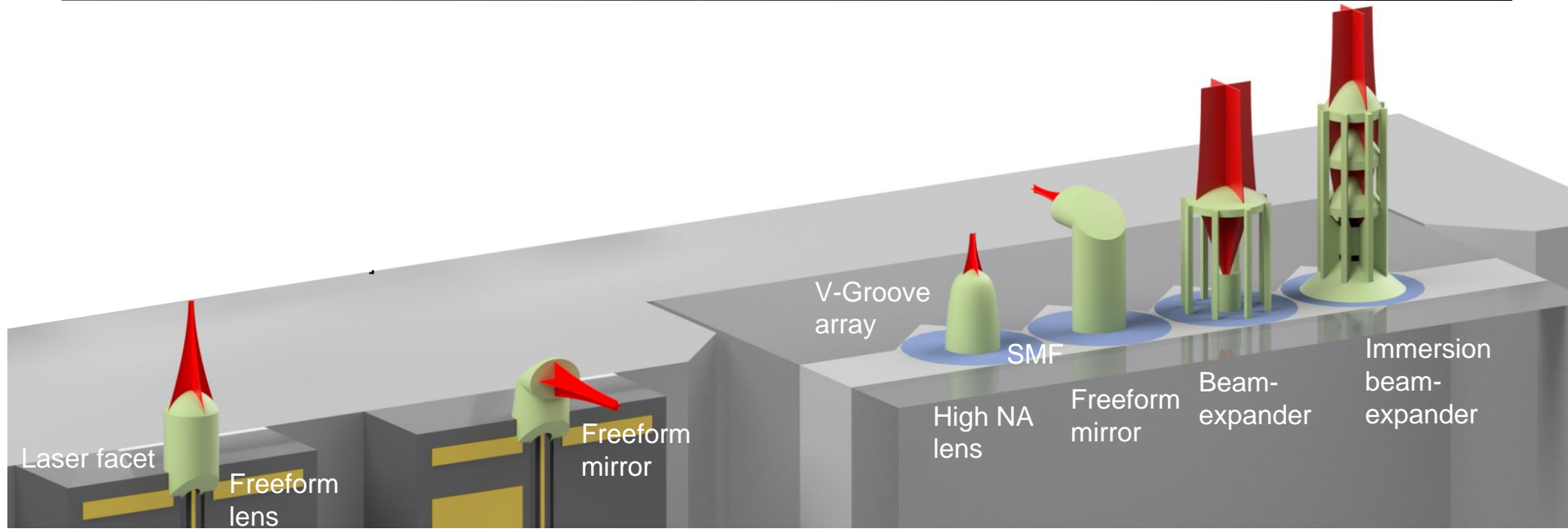
Lindenmann *et al.*, J. Light. Technol. **33**, 755-760 (2015)  
 Billah *et al.*, Optica **5**, 876-883(2018)

# Coupling by facet-attached micro-optical elements



Dietrich *et al.*, Nat. Photon. **12**, 241–247 (2018)

# Facet-attached micro-optical elements

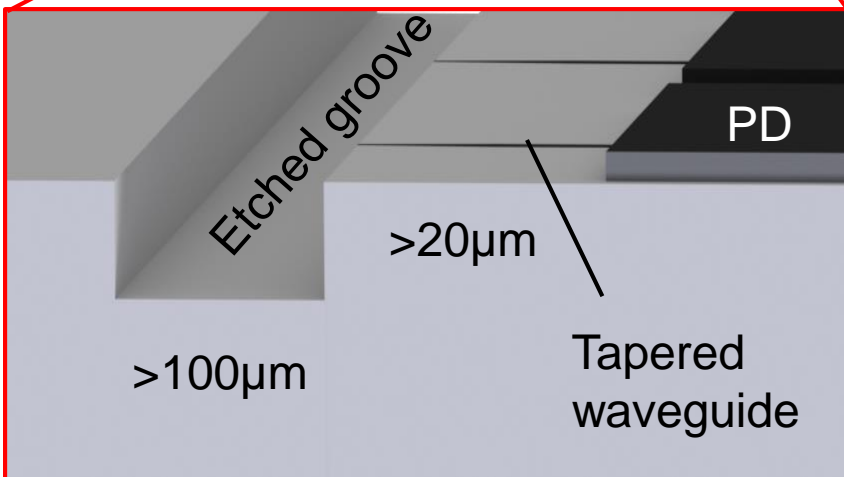
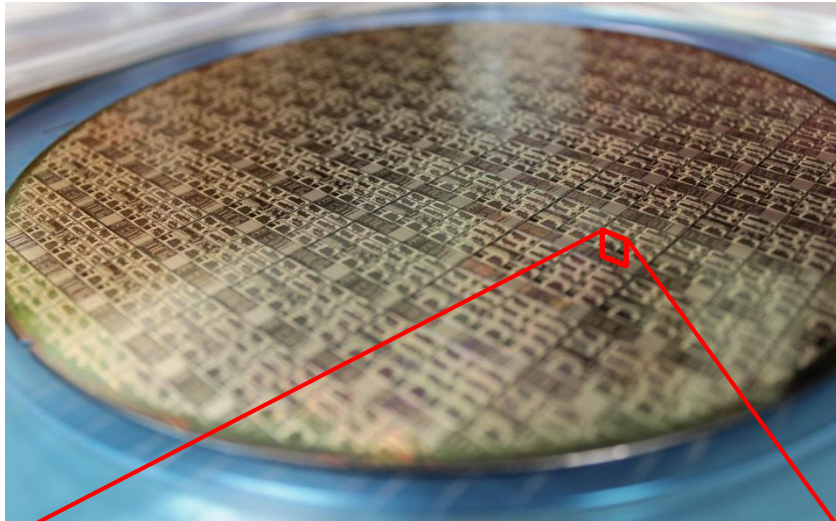


[www.vanguard-photonics.com](http://www.vanguard-photonics.com)

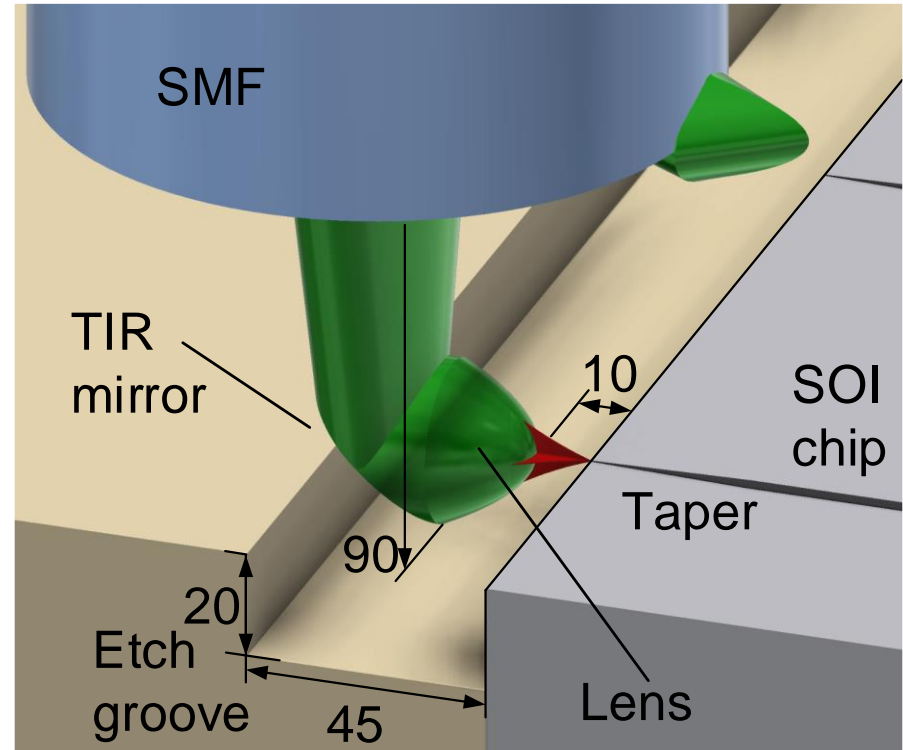
Dietrich *et al.*, Nat. Photon. **12**, 241–247 (2018)

# 3D-printed micro-optics for wafer-level probing

**Challenge:** Probing of edge-emitting devices prior to separation



Printing of **3D freeform facet-attached elements** for wafer-level probing



Reproducibility:  $\pm 0.2$  dB

Trappen *et al.*, ECOC 2018, paper Tu4C.2

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- Waveguides and passive devices
- Photodetectors
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## Summary

## Products:



### QSFP28 modules

- 100G-PSM4 MSA: 4 x 25 Gbit/s
- Reach up to 2 km

### Embedded optical modules

- 2x100G-PSM4 OptoPHY
- Reach up to 2 km

## Technology:

- pn-depletion-type Mach-Zehnder modulators
- Standard InP laser diode in silicon micro-package

## Products: QSFP28 pluggable transceivers



- 100G PSM4
- Reach up to 2 km



- 100G CWDM4
- Reach up to 10 km
- Data-center and 5G front-hauling

### Technology:

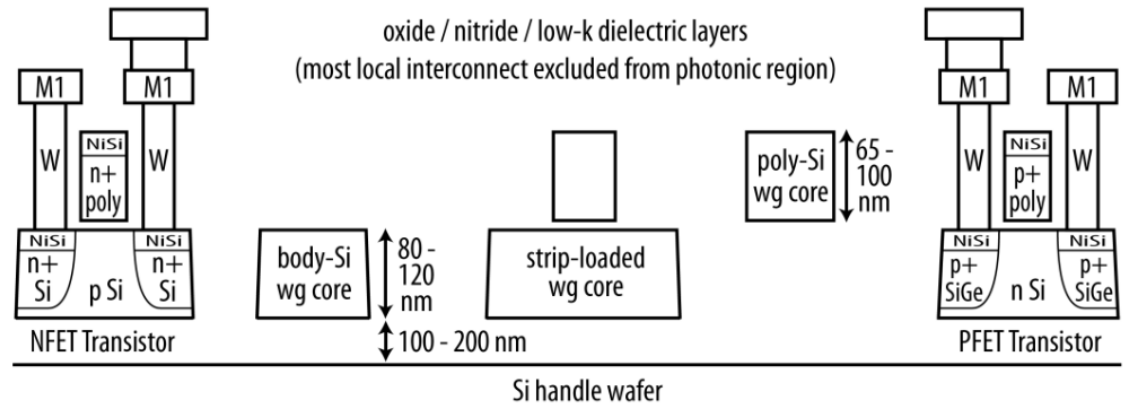
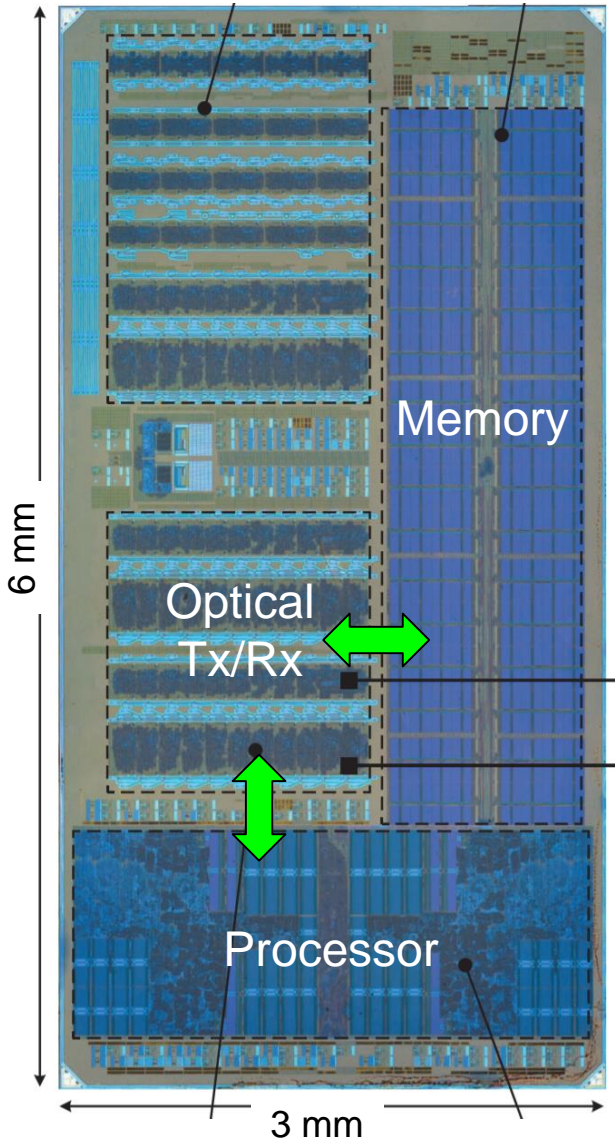
- pn-depletion-type Mach-Zehnder modulators
- “Hybrid laser”: Heterogeneous integration of III-V-dies on silicon photonic waveguides



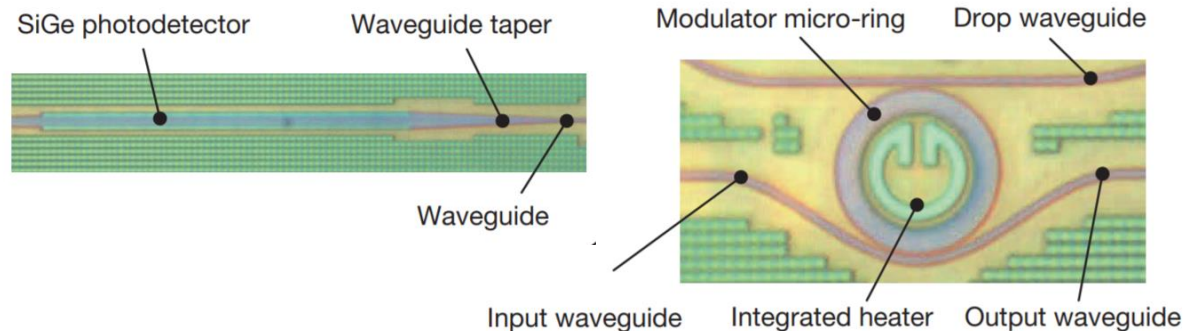
# Research demonstration: Silicon photonic transceivers co-integrated with electronics

## Communication between memory and processor by co-integrated silicon photonic transceivers

- Photonic device fabrication integrated into workflow of commercial 45-nm SOI process without adaptations
- Local removal of substrate to avoid topical leakage



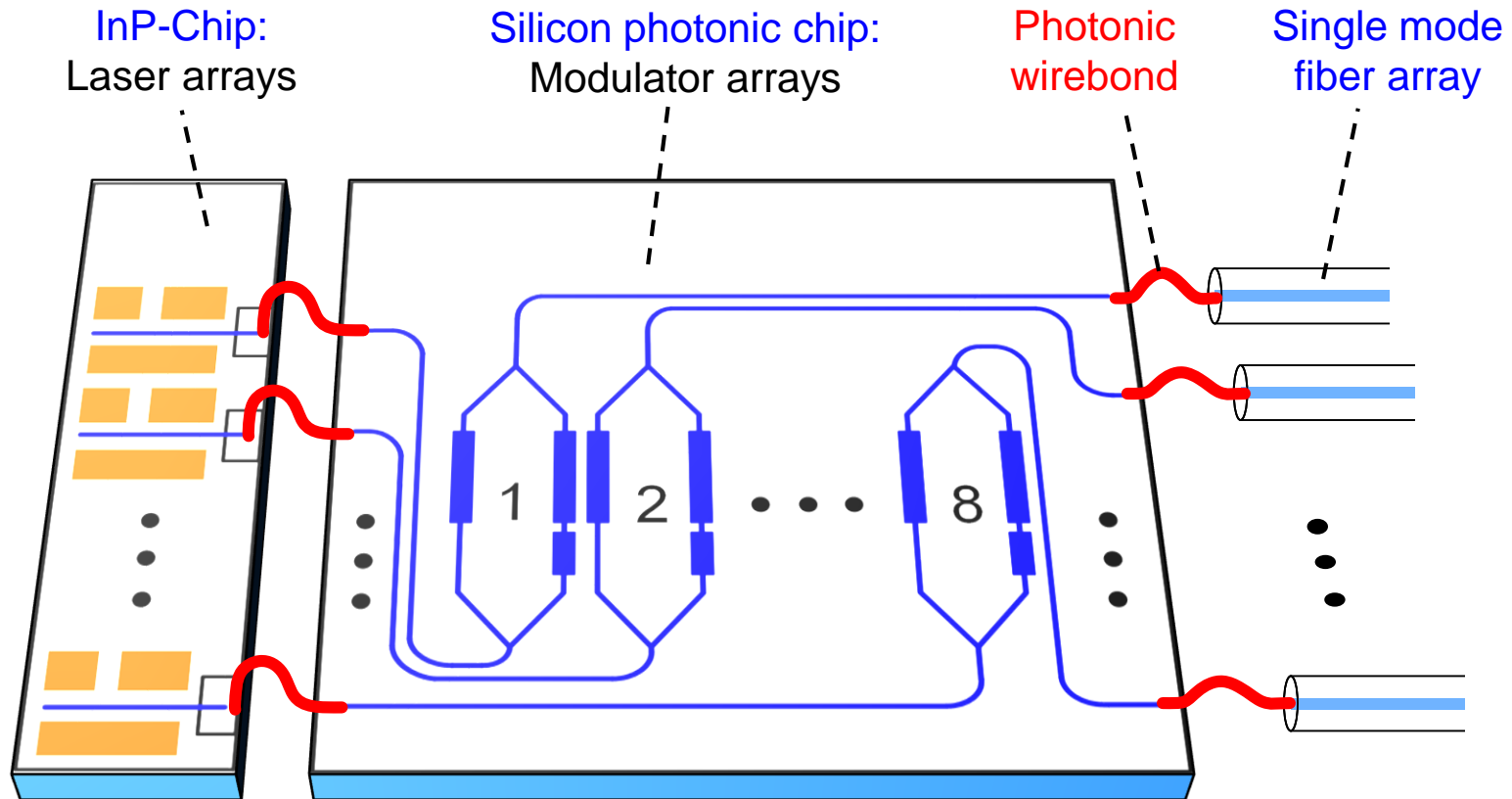
- External laser
- pn-type ring modulator, SiGe photodetector





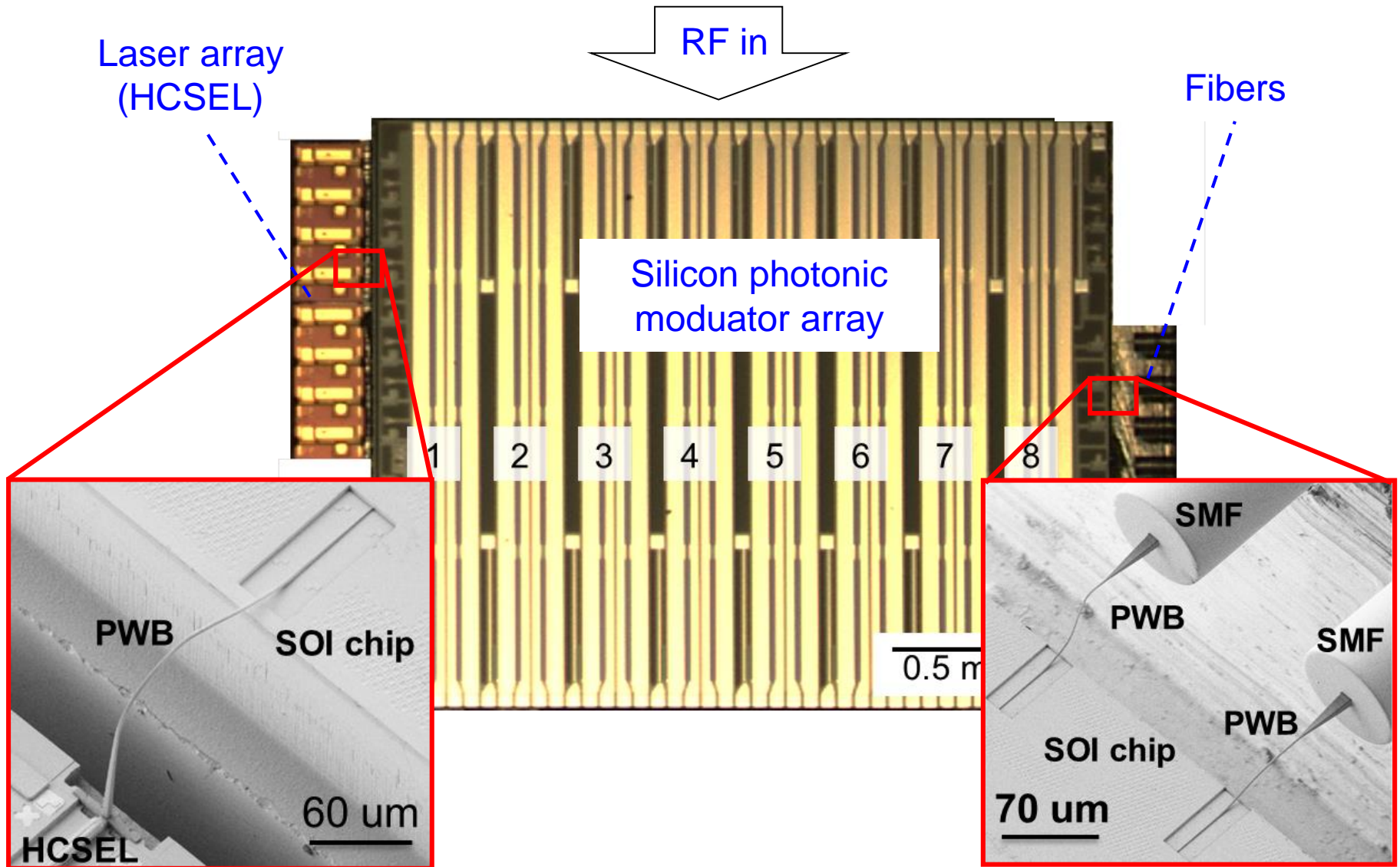
# Research demonstration: Multi-chip integration transmitter realized by photonic wire bonding

## Eight-channel silicon transmitter module

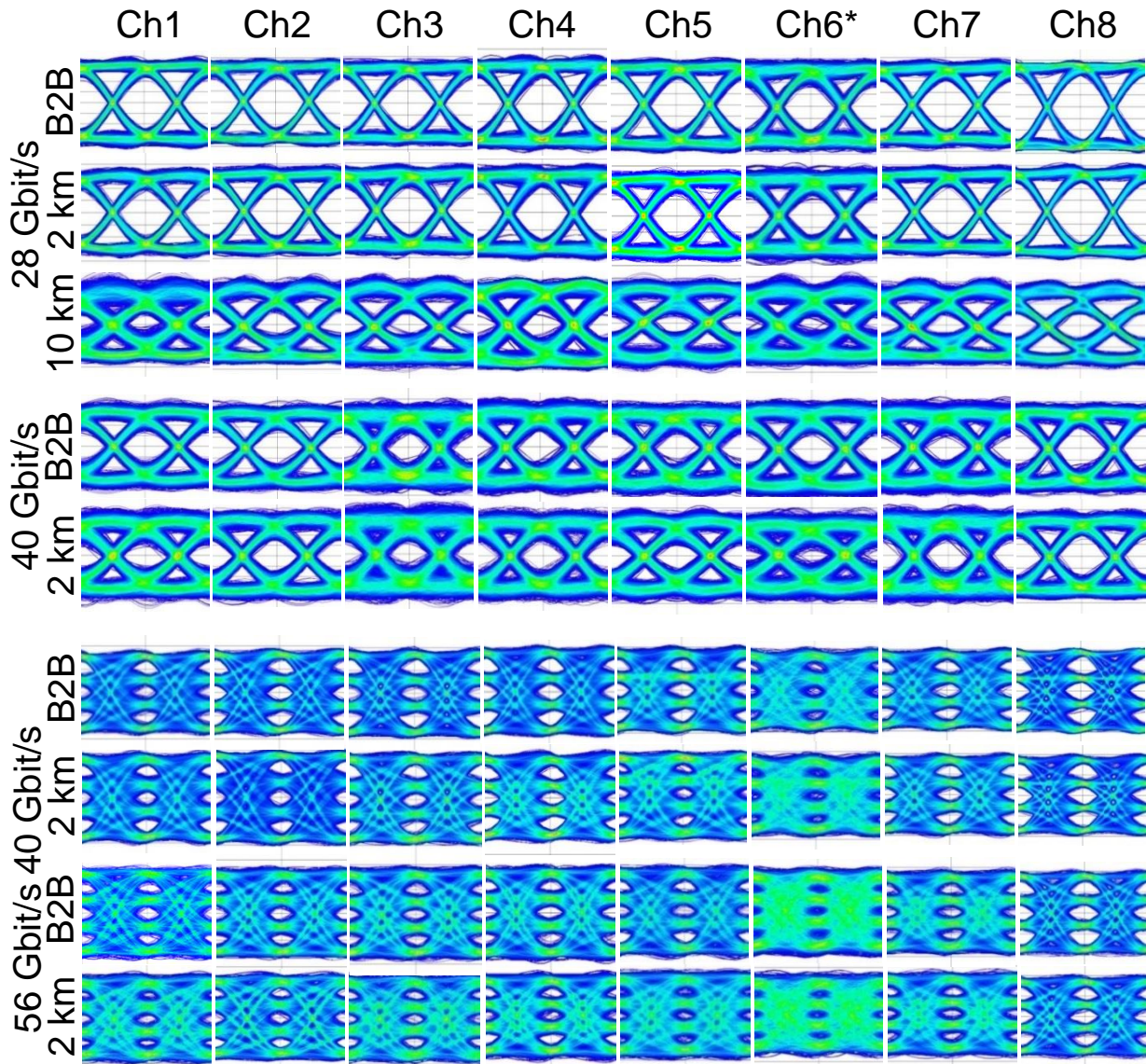


Billah *et al.*, OFC 2017, Th5D.6. (post-deadline paper)  
Billah *et al.*, ECOC 2017, paper Th.PDP.C.1 (post-deadline paper)

# Eight-channel silicon photonic transmitter module



# Data transmission at up to 448 Gbit/s



28 Gbit/s OOK (line rate 224 Gbit/s):  
 Error-free over 2 km  
 Below HD-FEC limit over 10 km

40 Gbit/s OOK (line rate 320 Gbit/s):  
 Below HD-FEC limit over 2 km

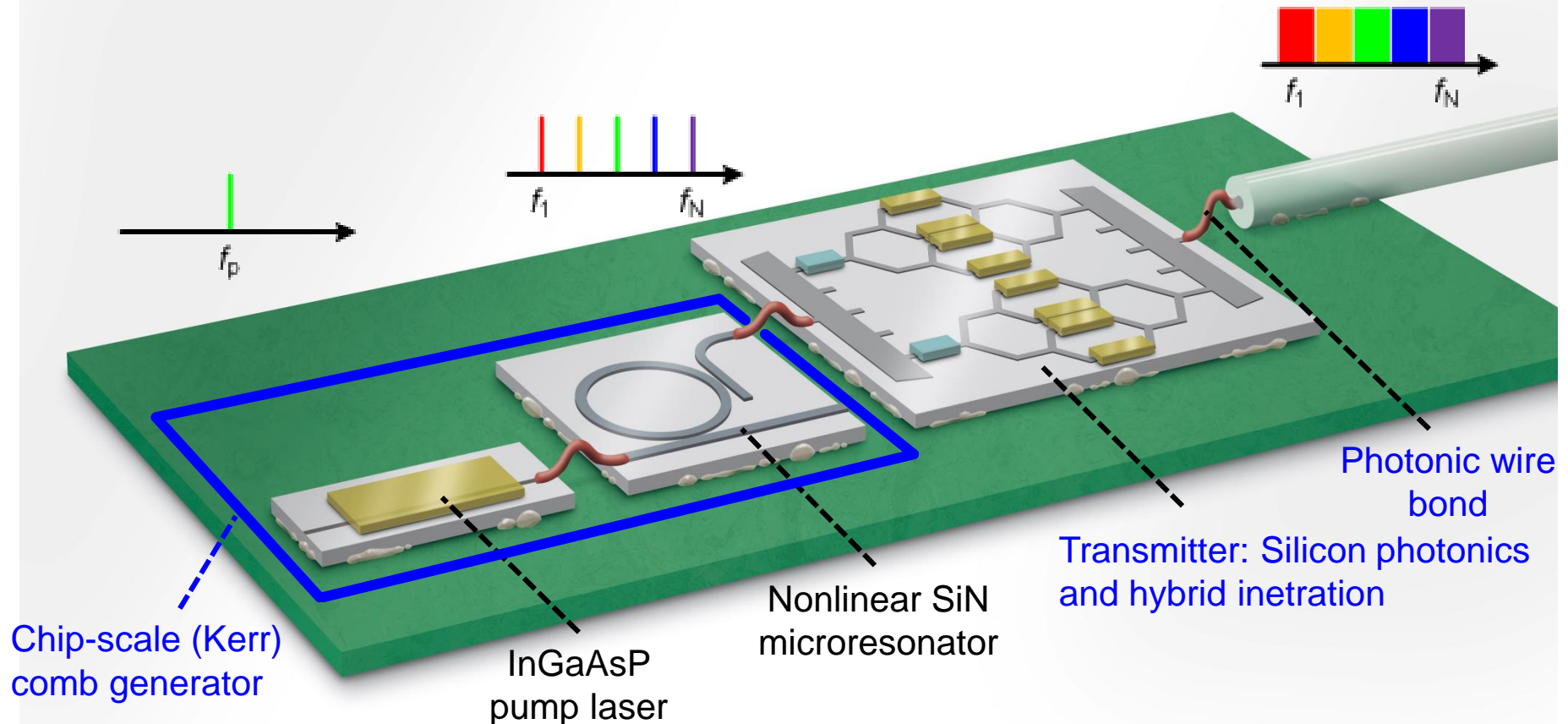
\* 3-dB tap!

40 Gbit/s PAM4 (line rate 320 Gbit/s):  
 Below HD-FEC over for 2 km  
 (except ch. 6)

56 Gbit/s PAM4 (line rate 448 Gbit/s):  
 Below HD-FEC limit over 2 km  
 (except ch. 6)

Billah *et al.*, OFC 2017,  
 Th5D.6. (post-deadline paper)

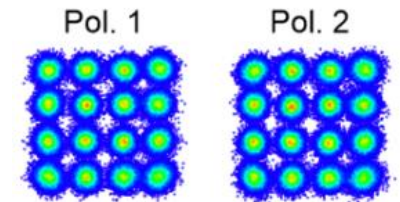
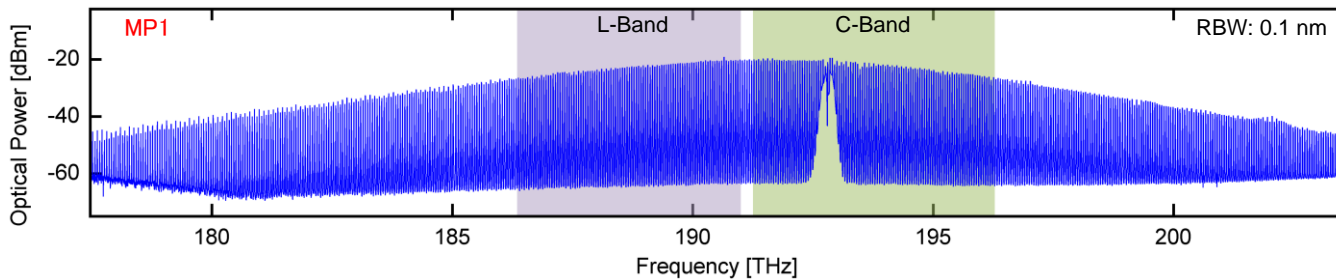
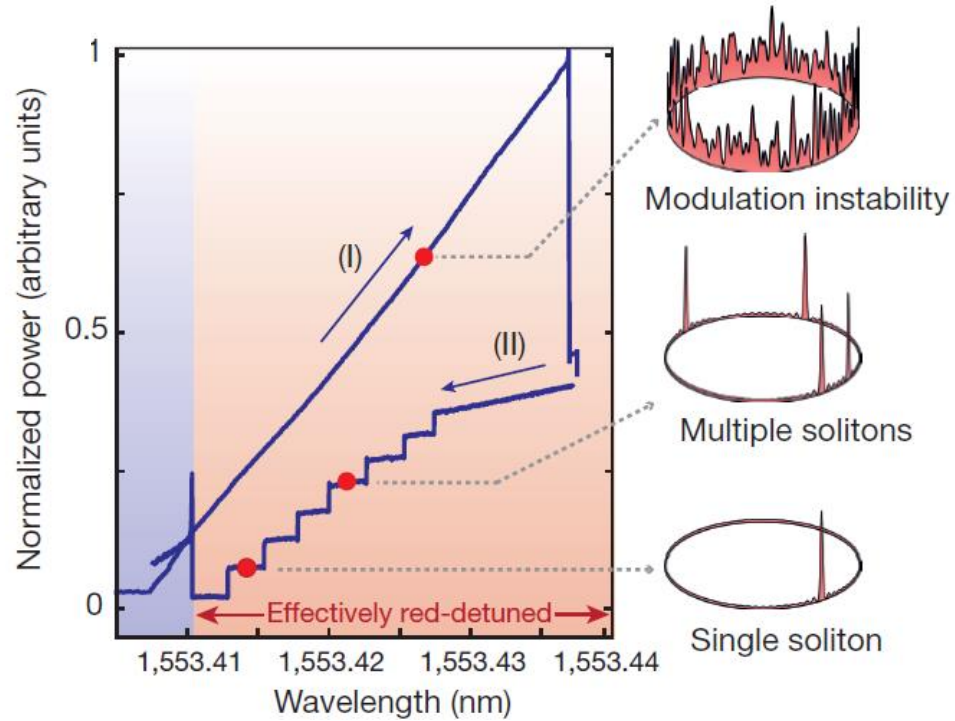
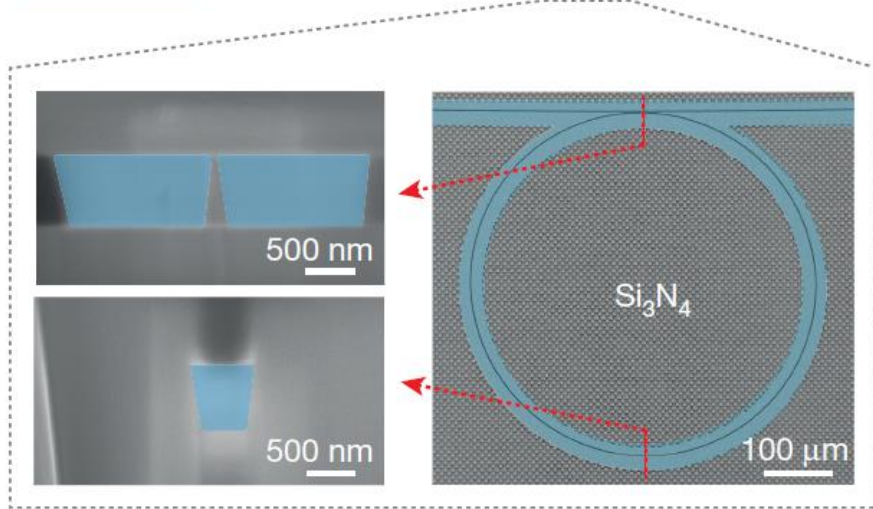
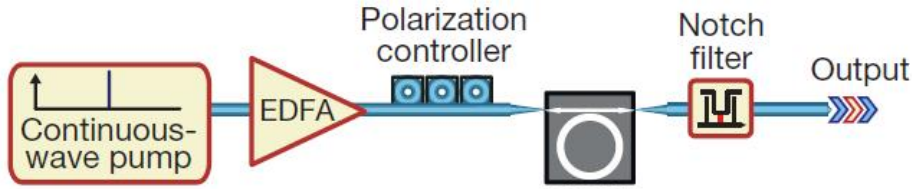
# Vision: Multi-Tbit/s transceivers using massively parallel WDM



Marin *et al.*, Nature **546**, 274–279 (2017)

Pfeifle *et al.*, Nat. Photon. **8**, 375 - 380 (2014)

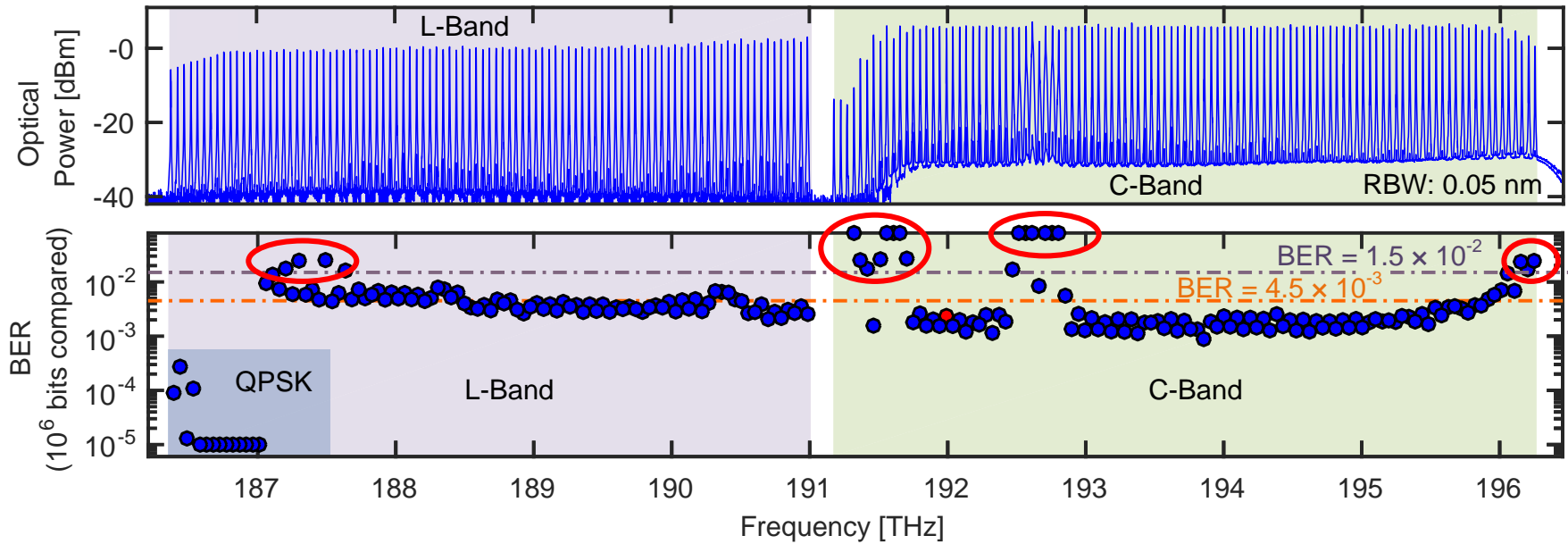
# Soliton Kerr comb generation



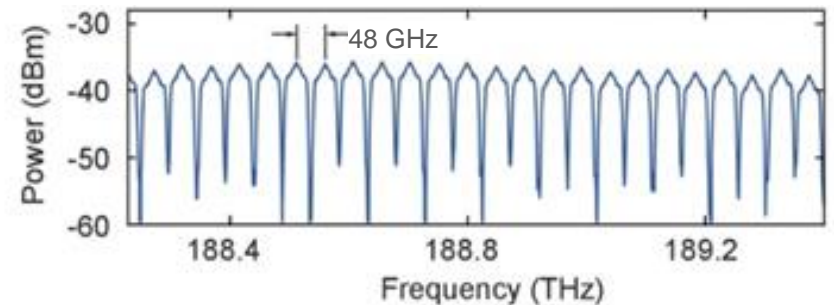
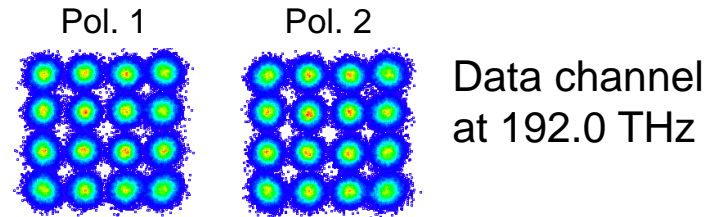
Transmission of **> 50 Tbit/s** on **179** carriers,  
derived from a pair of interleaved Kerr combs

Marin *et al.*, Nature **546**, 274–279 (2017)

# Interleaved soliton combs: Transmission at 50 Tbit/s



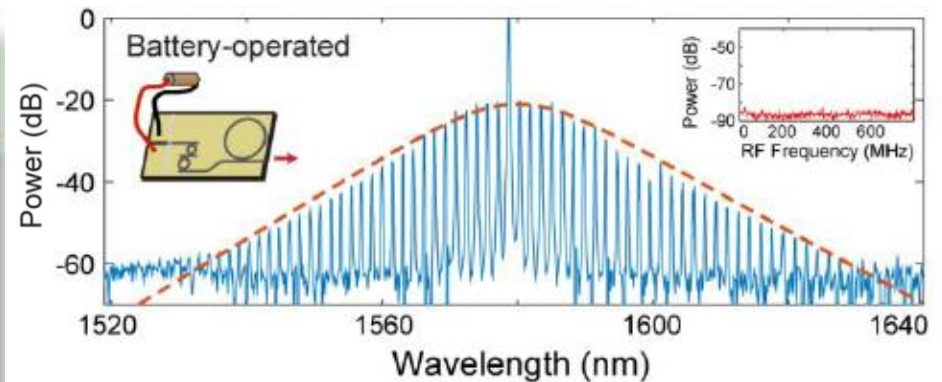
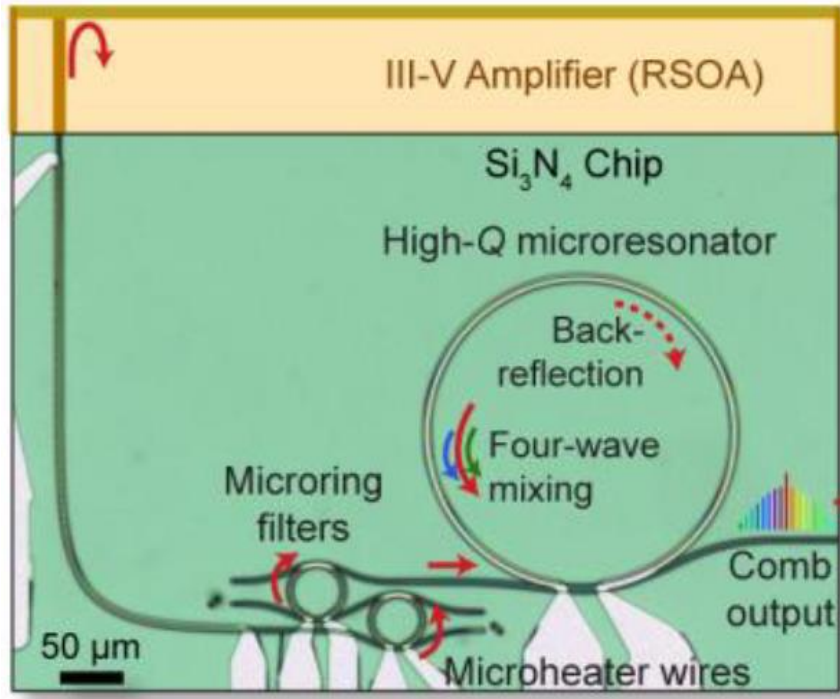
- 179 channels within FEC limits:  
165 × 40 GBd PDM-16QAM  
14 × 40 GBd PDM-QPSK
- Line rate (net data rate): 55 Tbit/s (50.2 Tbit/s)
- Impairments by limited amplifier bandwidth saturation power and filter mismatch (avoidable)
- High spectral efficiency: 5.6 bit/s/Hz



Marin *et al.*, Nature **546**, 274–279 (2017)

# Crucial: Low-power operation of soliton Kerr combs

Battery-driven integrated Kerr comb generator operated at  $\sim 10$  mW optical pump power



Intrinsic  $Q$ :  $(8.0 \pm 0.8) \times 10^6$

Pump wavelength aligned to resonance by narrowband back-reflection from Rayleigh scattering in microresonator

**Challenge:** Optical output power and power conversion efficiency (still) insufficient for data transmission in massively parallel silicon photonic circuits

Stern *et al.*, *Nature* **562**, 401–405 (2018)

**Other examples of low-power Kerr comb sources:**

Suh *et al.*, arXiv:1901.08126 (2019)

Liu *et al.*, *Optica* **5**, 1347-1353 (2018)

Yang *et al.*, *Nature Photonics* **12**, 297 (2018)

Raja *et al.*, *Nature Communications* **10**, 680 (2019)

## Introduction

- Scalability challenges in optical communications
- Silicon photonics and the need for hybrid integration

## Silicon-based building blocks for high-bandwidth transceivers

- Waveguides and passive devices
- Photodetectors
- Light sources
- Modulators

## Packaging and system assembly

- Coupling interfaces to silicon photonic waveguides
- In-situ waveguide fabrication by 3D laser lithography

## Silicon photonic transceivers

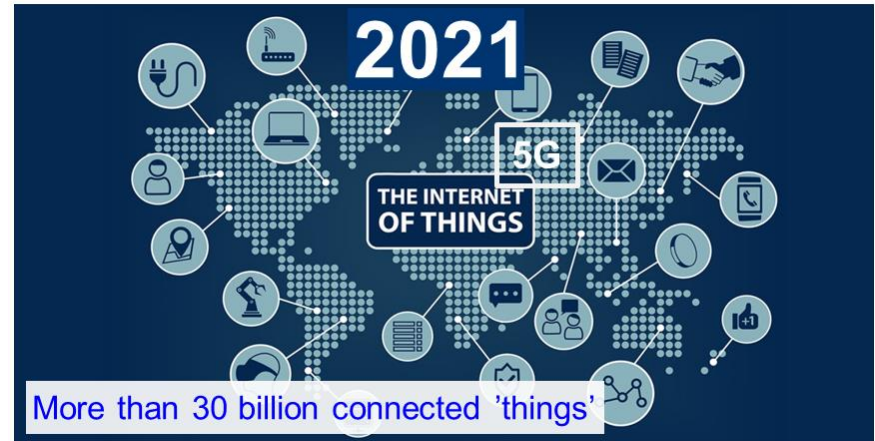
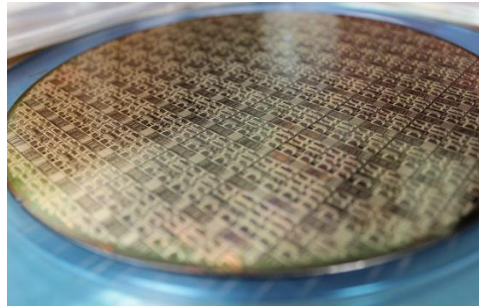
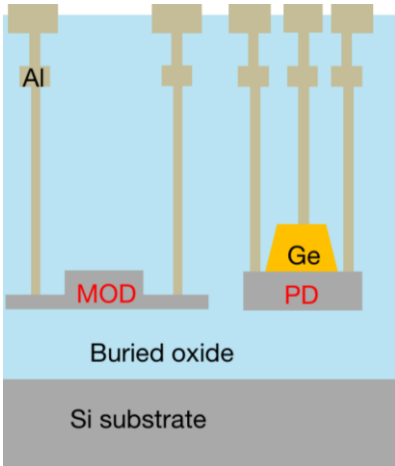
- Commercial products and experimental demonstrations
- Towards massively parallel WDM transceivers

## Summary



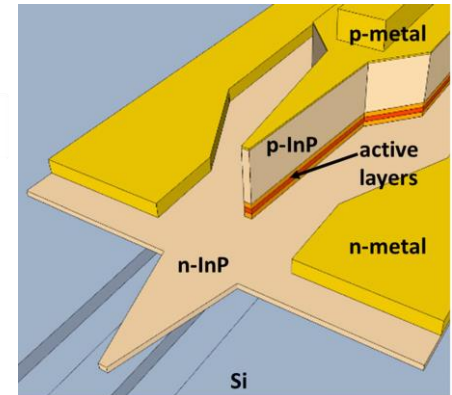
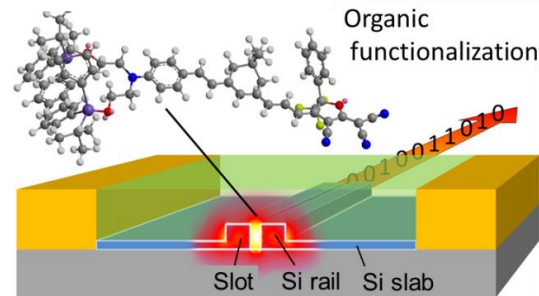
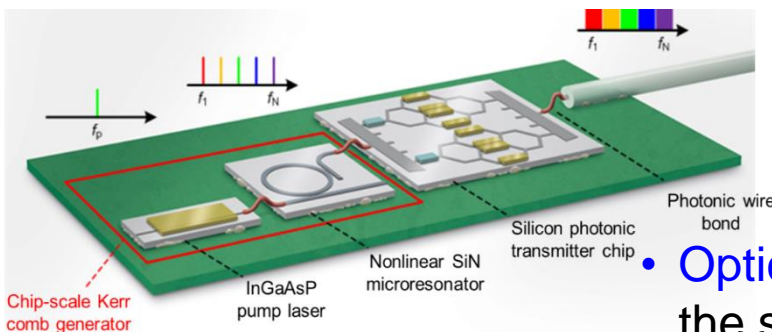
# Summary

- Future networks will rely on **massively parallel data transmission**.



- Silicon photonics** is a powerful platform, offering cost-efficient mass production of photonic circuitry at high yield.

- Deficiencies of silicon as an optical material can be overcome by **hybrid integration** on a chip and package level



- Optical frequency combs** might be key to fully exploit the scalability of the silicon photonic platform.

